

History of Moiré

~ Applications to Shape, Deformation and Strain Measurement ~

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Shien RI (AIST, Japan)



American Indian (Hopi)
Pottery

His story of Harry Moiré ~ Applications to Shape, Deformation and Strain Measurement ~

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Harry Moiré

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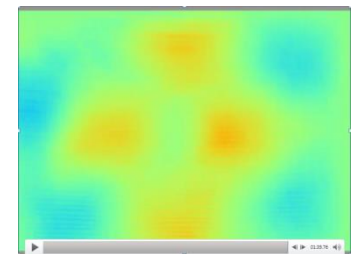
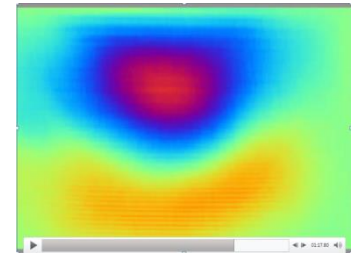
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Vibration mode

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- His story of Harry Moiré
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- Author's current research
 - Whole-space tabulation method
 - Light-source stepping method
 - Sampling moiré method
 - One-pitch phase analysis (OPPA)

His story of Harry Moiré ~ Applications to Shape, Deformation and Strain Measurement ~

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Harry Moiré

My dream in my childhood

- Same birthday as Thomas Edison
→ Inventor
- Same handicap as Hideyo Noguchi
→ Scientist



**Big inventor or
Scientist**

His story of Harry Moiré

1944 Born in **Osaka, Japan**

1968 Graduated Master Course of **Osaka University**

1968 **Komatsu MFG**, Researcher

1974 Faculty of Engineering Science, **Osaka University**

1989-1990 Visiting Professor of **Virginia Tech** (VPISU)

1993 Faculty of Economics, **Wakayama University**

1995 Faculty of Systems Engineering, WU

2004 Executive Board (Vice-president) , WU

2009 Established **Moiré Institute Inc.** (Representative director)

2012 Established **4D Sensor Inc.** (Chairman)

Research by Harry Moiré

1965 Photoelasticity, Moiré method

1966 Stress wave propagation analysis by
photoelasticity and high-speed camera

1968 Finite element method

1974 Powder compaction & impact phenomena

1980 Image processing

1984 Scanning moiré by TV

:

:

:

Accomplished research

Optical methods and image processing for shape, deformation, and stress and strain measurement.

- 1) **Scanning moiré method**, phase-shifting scanning moiré method
- 2) Phase analysis methods using **Fourier, wavelet and Gabor** transforms
- 3) **Strain rate distribution** measurement by original **high-speed video** camera
- 4) Real-time phase analysis by **Integrated phase-shifting method**
- 5) Shape measurement by **frequency modulated grating** projection
- 6) Real-time analysis of **photoelasticity** and **moiré interferometry**
- 7) Shape measurement by **multi-reference planes**
- 8) Subnanometer displacement measurement by windowed phase-shifting digital **holographic interferometry**

Current research

Development of high-speed, highly-accurate and low cost measurement systems using some optical methods and image processing for shape, deformation, and stress and strain measurement

- 1) Grating projection method using whole space tabulation method (Shape)
- 2) Grating projection method using LED line light sources (Shape)
- 3) Sampling moiré method (Displacement and shape)
- 4) One-Pitch Phase Analysis (OPPA) method (Shape and displacement)

4D Sensor Inc., Wakayama

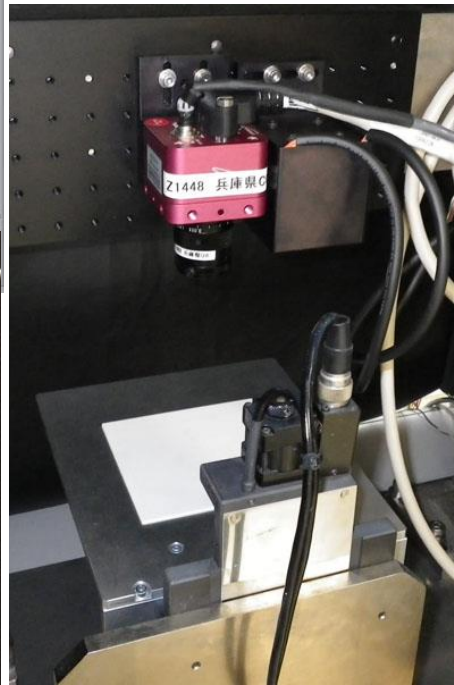
Venture Company generated from WU



Products



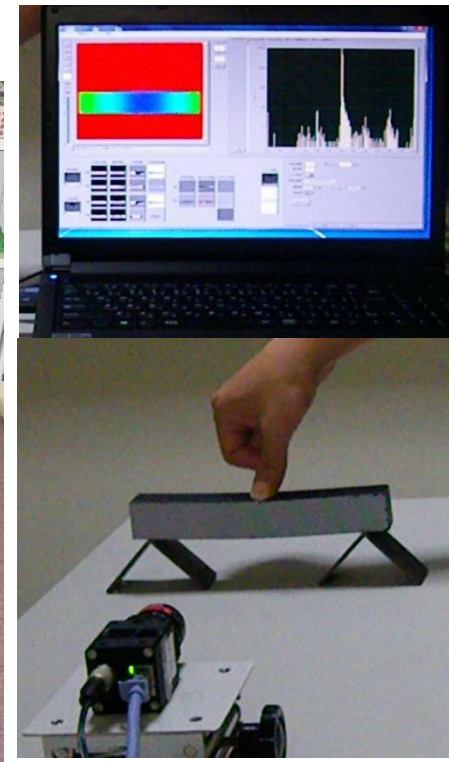
3D camera



4D camera



Shadow
moiré camera



Sampling
moiré camera

High-speed, high accuracy, compact and low price

Academic Societies for Exp. Mech.

1847 Institution of Mechanical Engineers

1880 American Society of Mechanical Engineers

1916 Optical Society of America

1941 American Society for Non-destructive Testing

1943 (1985) Society for Experimental Mechanics (SESA,
SEM)

1955 International Society for Optical Engineering (SPIE)

1959 (1998) European Association for Experimental
Mechanics (EURASEM)

1964 British Society for Strain Measurement (BSSM)

Academic Societies for Exp. Mech. in Japan

1879 Japan Society of Civil Engineers

1886 Architectural Institute of Japan

1897 The Japan Society of Mechanical Engineers

1933 The Japan Society for Precision Engineering

1934 The Japan Society for Aeronautical and Space Sciences

1952 The Japanese Society for Non-Destructive Inspection

1952 The Optical Society of Japan

1952 The Society of Materials Science, Japan

1975 Japanese Society for Moiré Contourography

1979 (2001) The Japanese Society for Experimental Mechanics
(JSP, JSEM)

Int. Conf. on Exp. Mech.

- XIII SEM Int. Congress 2016 (SEM, every four years)
- International Conference on Experimental Mechanics ICEM 17 (2016). (EURASEM, every four years → every two years)
- The 14th Asian Conference on Experimental Mechanics (ACEM14) (ACEM → ASEM, every year)
- The International Conference on Advanced Technology in Experimental Mechanics 2015 (JSME, every two years → every four years in ACEM)
- 10th International Conference on Advances in Experimental Mechanics (BSSM, every two years)
- The 10th International Symposium on Advanced Science and Technology in Experimental Mechanics (JSEM, Every year)
- 30th DANUBIA-ADRIA, SYMPOSIUM ON ADVANCES IN EXPERIMENTAL MECHANICS (every year)

History of ATEM and ACEM

- ATEM organized by JSME-MMD
- 1st ATEM, Kanazawa, 1993 (Miyano)
- 2nd ATEM, Tokyo, 1995 (Takashi)
- 3rd ATEM, Wakayama, 1997 (Morimoto)

:

- SEM & ICEM
- Big conf. in Asia
- To adjust, certify and support

- Asian Liaison Committee on Exp. Mech. (ACEM) established in 1997
- Asian Conference on Experimental Mechanics (ACEM) organized by Asian Committee for Experimental Mechanics (ACEM)
- 1st ACEM, Taipei, 2002
- 2nd ACEM, Nagoya, 2003
- 3rd ACEM, Singapore 2004

:

- Asian Conference on Experimental Mechanics (ACEM) was renamed as Asian Society for Experimental Mechanics (ACEM) in Singapore, 2009

History of Moiré Method ~ Applications to Shape, Deformation and Strain Measurement ~

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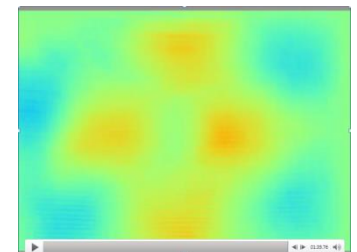
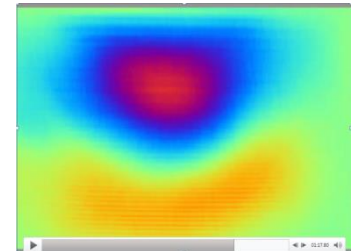
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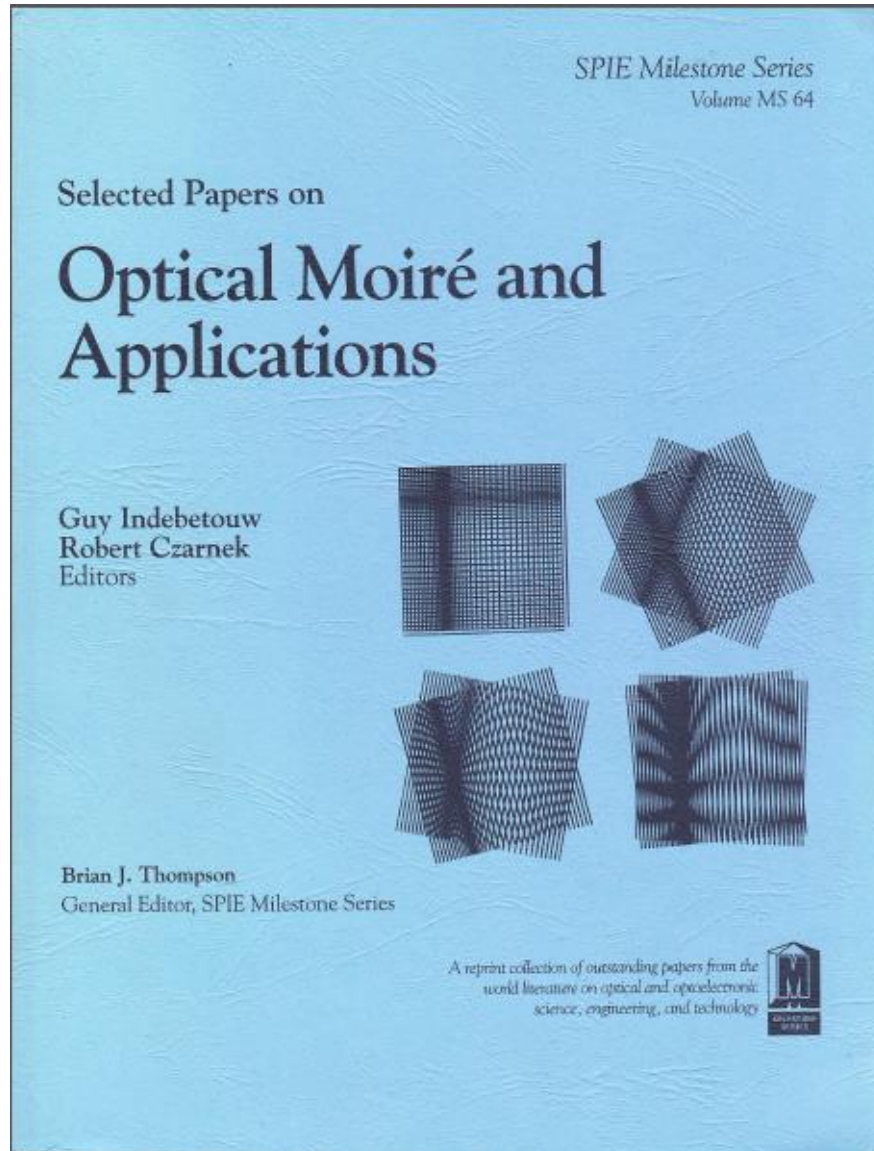
*Motoharu FUJIGAKI (University of
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Vibration Mode

Historical review of moiré method¹⁷



Selected Papers on
Optical Moiré and
Applications
Editor(s): Guy J. M. Indebetouw;
Robert Czarnek, 1992

92 papers from 1874-1984
648 pages

Spie Press Book • **on sale**

Member Price \$85.00 ~~\$100.00~~

Non-Member Price \$100.00 ~~\$118.00~~

Selected Papers on Optical Moiré and Applications¹⁸

92 papers, Editor(s): Guy J. M. Indebetouw; Robert Czarnek, 1992

Optics 1977)

558 Moiré topography, sampling theory, and charge-coupled devices B.W. Bell, C.L. Koliopoulos (Optics Letters 1984)

561 Interactive fringe analysis system: applications to moiré contourgram and interferometry T. Yatagai, M.

Idesawa, Y. Yamaashi, M. Suzuki (Optical Engineering 1982)

567 Automatic moiré contouring H.E. Cline, W.E. Lorensen, A.S. Holik (Applied Optics 1984)

573 Digital-filtering techniques applied to the interpolation of moiré-fringes data C.A. Sciammarella, D.L. Sturgeon
(Experimental Mechanics 1967)

581 Fourier-transform method of fringe-pattern analysis for computer-based topography and interferometry M.

Takeda, H. Ina, S. Kobayashi (Journal of the Optical Society of America 1982)

Chapter Ten

Additional Applications and Manifestations of Moiré Phenomena

Moiré Synthesis and Use in Optical Processing

589 Zur Messung des optischen Übertragungsfaktors A. Lohmann (Optik 1957)

596 On moiré fringes as Fourier test objects A. Lohmann (Applied Optics 1966)

597 Variable Fresnel zone pattern A.W. Lohmann, D.P. Paris (Applied Optics 1967)

601 Moiré optical spatial correlator O. Kafri, T. Chin, D.F. Heller (Optics Letters 1984)

Moiré for Alignment

604 Moiré fringes as visual position indicators L.O. Vargardy (Applied Optics 1964)

610 Photolithographic mask alignment using moiré techniques M.C. King, D.H. Berry (Applied Optics 1972)

615 A new interferometric alignment technique D.C. Flanders, H.I. Smith, S. Austin (Applied Physics Letters 1977)

Moiré in Halftoning and Array Detectors

618 Moiré interference phenomena in halftone printing D. Tollenaar (Amsterdam Instituut voor Grafische Techniek
1945; translated by E. Weiblen, for Research and Engineering Council of the Graphic Arts Ind. Inc., Arlington,
Va., 1964)

634 Moiré patterns in scanned halftone pictures A. Steinback, K.Y. Wong (Journal of the Optical Society of America
1982)

Historical review of moiré method 19

(There are too many important other papers)

- 1874 Rayleigh
 - 1874 Manufacture and theory of diffraction-gratings
- 1948 Weller & Shepard
 - 1948 Displacement measurement
- 1956 Guild
 - 1956 Moiré interferometry
- 1967 Sciammarella & Sturgion
 - 1967 Multiplication and digital filtering
- 1968 Chiang, Parks & Durelli
 - 1968 Moiré-fringe interpolation and multiplication
- 1969 Theocaris
 - 1969 Isopachics (Shadow moiré)
- 1970 Takasaki
 - 1970 Moiré topography
- 1971 Post
 - 1971 Moiré fringe multiplication
- 1971 Hovanesian & Hung
 - 1971 Moiré contour-sum contour-difference, and vibration
- 1974 Bruning et. al.
 - 1974 Phase-shifting method
- 1977 Idesawa, Yatagai & Soma
 - 1977 Scanning moiré method
- 1982 Takeda, Ina & Kobayashi
 - 1982 Fourier-transform method

On the manufacture and theory of diffraction-gratings, **Lord Rayleigh** (London, Edinburgh, and Dublin Philosophical Magazine 1874 & 1881)

Digital wavefront measuring interferometer for testing optical surfaces and lenses

J.H. Bruning, D.R. Herriott, J.E. Gallagher, D.P. Rosenfeld, A.D. White, D.J. Brangaccio
(Applied Optics 1974)

Selected Papers on Optical Moiré and Applications

92 papers, Editor(s): Guy J. M. Indebetouw; Robert Czarnek, 1992

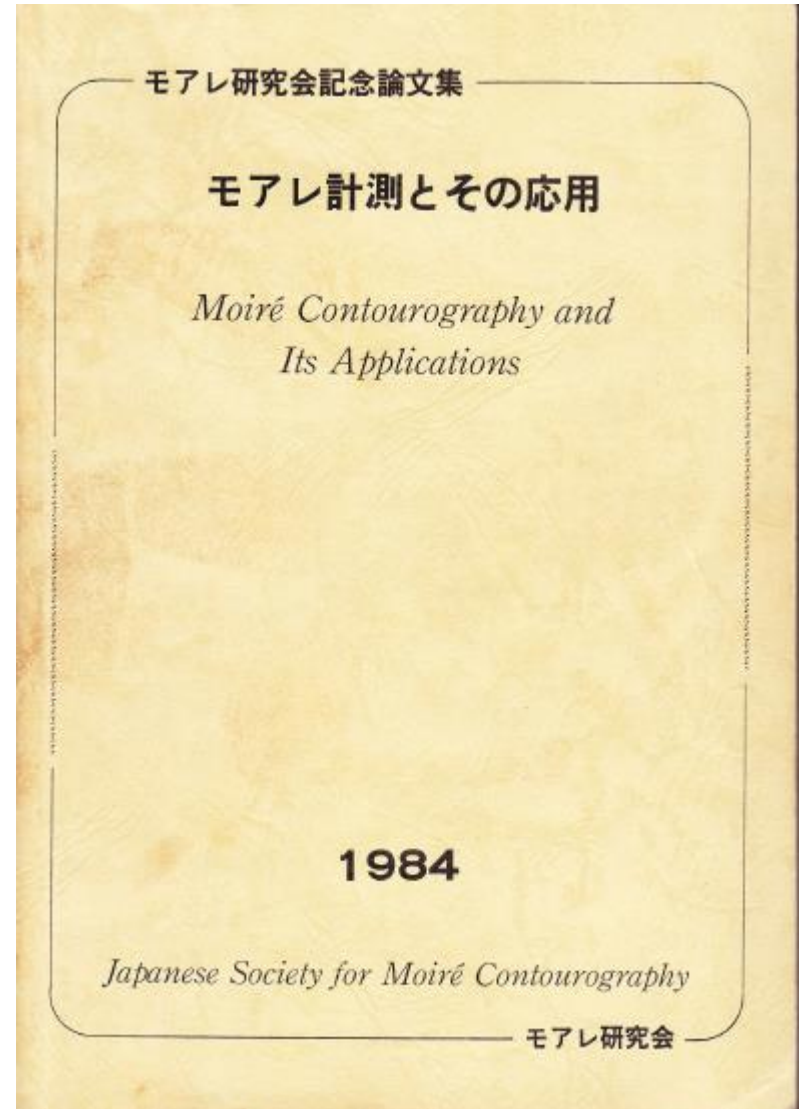
- A new type of interference fringes observed in electron-micrograph of crystalline substance **T. Mitsuishi**, H. Nagasaki, R. Uyeda (Proceedings of the Japan Academy 1951)
- Moiré patterns: their application to refractive index and refractive index gradient measurements **Y. Nishijima**, G. Oster (Journal of the Optical Society of America 1963)
- Moiré patterns G. Oster, **Y. Nishijima** (Scientific American 1963)
- Interferometric generation of contour lines on opaque objects **T. Tsuruta**, Y. Itoh (Optics Communications 1969)
- Moiré topography **H. Takasaki** (Applied Optics 1970)
- Interpretation of the moiré method for obtaining contours of equal slope from an inteferogram **S. Yokozeki**, T. Suzuki (Applied Optics 1970)
- Shearing interferometer using the grating as the beam splitter **S. Yokozeki**, T. Suzuki (Applied Optics 1971)
- Shearing interferometer using the grating as the beam splitter. Part 2 **S. Yokozeki**, T. Suzuki (Applied Optics 1971)
- Moiré topography by means of a grating hologram **Y. Yoshino**, M. Tsukiji, H. Takasaki (Applied Optics 1976)
- Scanning moiré method and automatic measurement of 3-D shapes **M. Idesawa**, T. Yatagai, T. Soma (Applied Optics 1977)
- Fourier-transform method of fringe-pattern analysis for computer-based topography and interferometry **M. Takeda**, H. Ina, S. Kobayashi (Journal of the Optical Society of America 1982)
- Interactive fringe analysis system: applications to moiré contourogram and interferometry **T. Yatagai**, M. Idesawa, Y. Yamaashi, M. Suzuki (Optical Engineering 1982)

Historical topics of moiré in Japan

1975 Establishment of
Japanese Society for
Moiré Contourography

1984 Book Publishing of
Moiré Contourography
and Its Applications :
10th Annual Meeting :
Selected Papers and
Abstracts,
Japanese Society for
Moiré Contourography
(in Japanese)

59 papers from 1970-1984,
474 pages



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High-sensitivity moiré topography	Preliminary	モアレ法による摩擦定数の測定 (高分子論文集, 1981)	岡部 啓, 渋谷 香, 松田 英臣.....	439
モアレ縞自動測定	モアレ	New method of measurement of dynamic Poisson's ratio by high speed moiré topography.	T. TSUNO, Y. NAKAMURA.....	446
		New method of measurement of dynamic Young's modulus by high speed moiré topography. (SPIE volume 348, 1982)	T. TSUNO, Y. NAKAMURA.....	450
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A new type of interference fringes observed in electron-micrograph of crystalline substance

T. Mitsubishi, H. Nagasaki, R. Uyeda (Proceedings of the Japan Academy 1951)

Moiré patterns: their
application to refractive
index and refractive
index gradient
measurements, G. Oster,
Y. Nishijima (Scientific
American 1963)

Moiré patterns G. Oster,
Y. Nishijima (Scientific
American 1963)

Moiré topography
H. Takasaki
(Applied Optics 1970)

Scanning moiré method and automatic measurement of 3-D shapes,
M. Idesawa, T. Yatagai, T. Soma
(Applied Optics 1977)

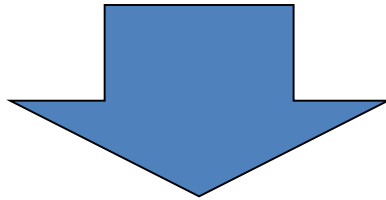
Interactive fringe analysis system: applications to moiré contourgram and interferometry
T. Yatagai, M. Idesawa, Y. Yamaashi, M. Suzuki
(Optical Engineering 1982)

Fourier-transform method of fringe-pattern analysis for computer-based topography and interferometry
M. Takeda, H. Ina, S. Kobayashi
(Journal of the Optical Society of America 1982)

Current research by authors

Purpose

To develop high-speed, high-accuracy, compact and low-cost
Shape measurement systems for moving objects

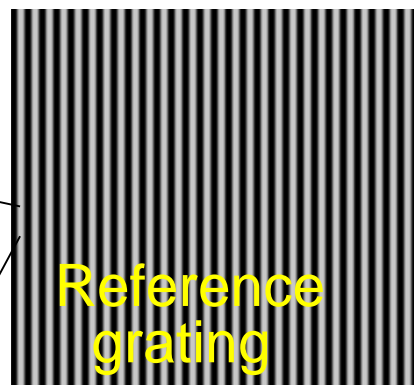
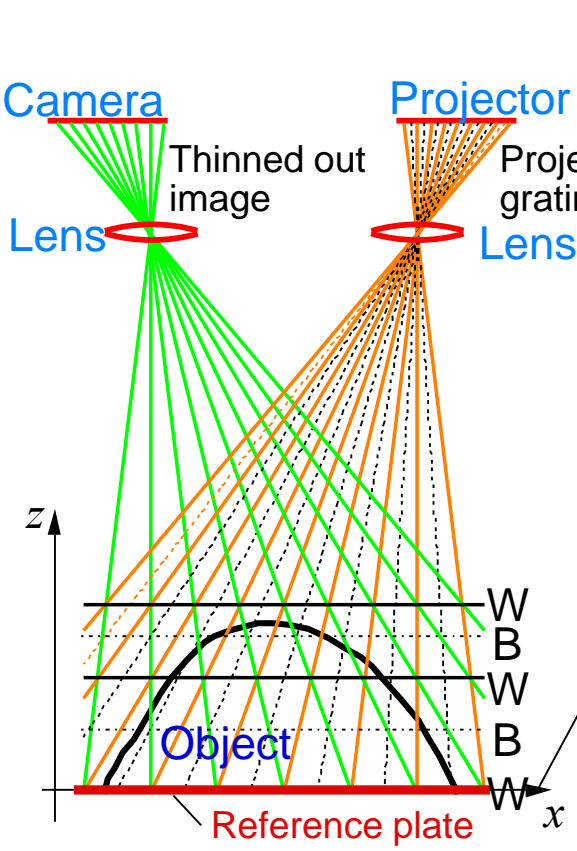


- Grating method
- Moiré method

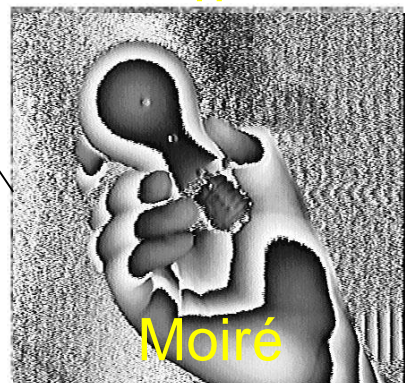
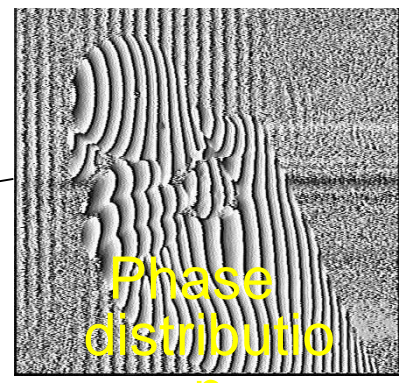
Techniques

- Phase shifting method
- Whole-Space Tabulation Method (WSTM)
- Light-source-stepping method
- Light-source-stepping shadow moiré method
- Sampling moiré method
- One-Pitch Phase Analysis (OPPA) method

Procedure of shape measurement using grating projection method



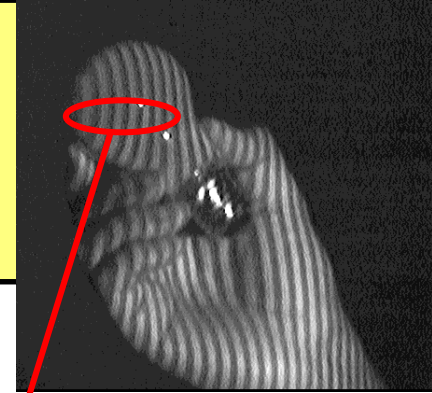
1. Projected grating
2. Phase analysis
3. Phase difference between object and reference plane



Moiré topography

Lens, grating and image plane should be parallel to reference plane

Phase analysis of fringe or grating pattern



Intensity (Brightness)

$$I = a \cos \theta + b$$

a : Amplitude
 θ : Initial phase
 b : Background

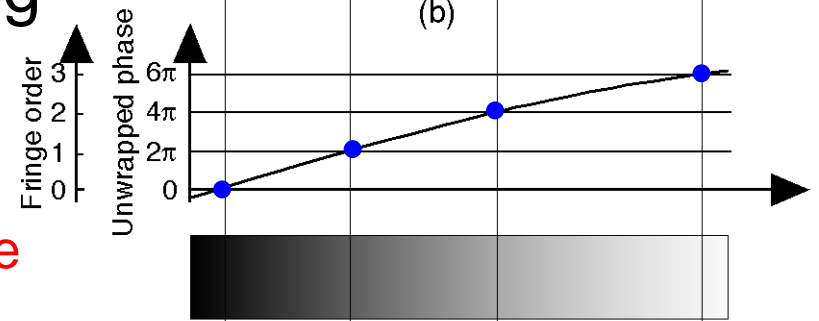
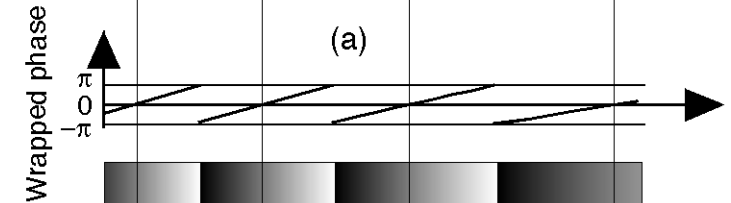
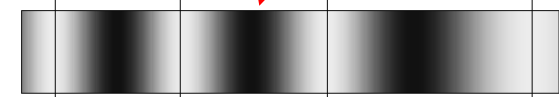
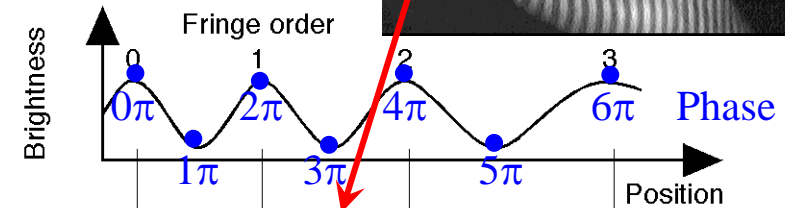
} Unknown

The phase θ of fringe or grating corresponds to displacement, height, etc.

Intensity during phase-shifting

$$I = a \cos(\theta + \alpha) + b$$

α : Phase-shift



(c) Relationship between brightness and phase of grating pattern

- Phase analysis provides accurate shape (Resolution: 1/100~ 1/1000 of pitch)
- Unwrapping provides a large dynamic range.

Phase-shifting method using many images

29

Intensity (brightness) distribution

N : Number of grating or fringe images for one period

Phase-shift amount

$$\Psi = \frac{2\pi}{N} \quad \alpha = n\Psi$$

N should be an integer.

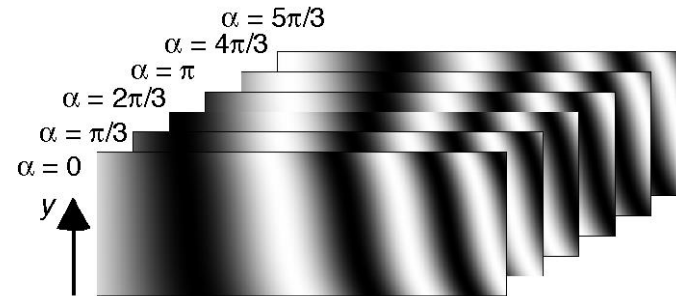
Brightness of n th image

$$I_n = a \cos(\theta + n\Psi) + b$$

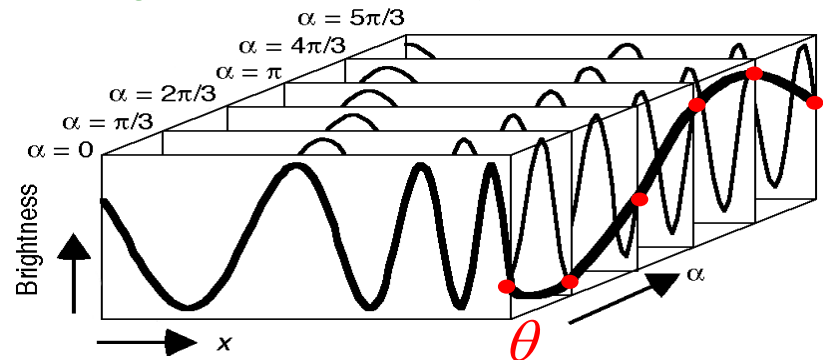
Initial phase θ

$$\tan \theta = - \frac{\sum_{n=0}^{N-1} I_n \sin(n \frac{2\pi}{N})}{\sum_{n=0}^{N-1} I_n \cos(n \frac{2\pi}{N})}$$

$$I = a \cos \theta + b$$



3D images obtained by phase-shifting



Brightness distribution and brightness change

Usually, $N=4$ is used.

Large number of phase shifting provides accurate result. ($N=16$)

It corresponds to the extraction of frequency 1 of Fourier transform

(Smoothest wave extraction)

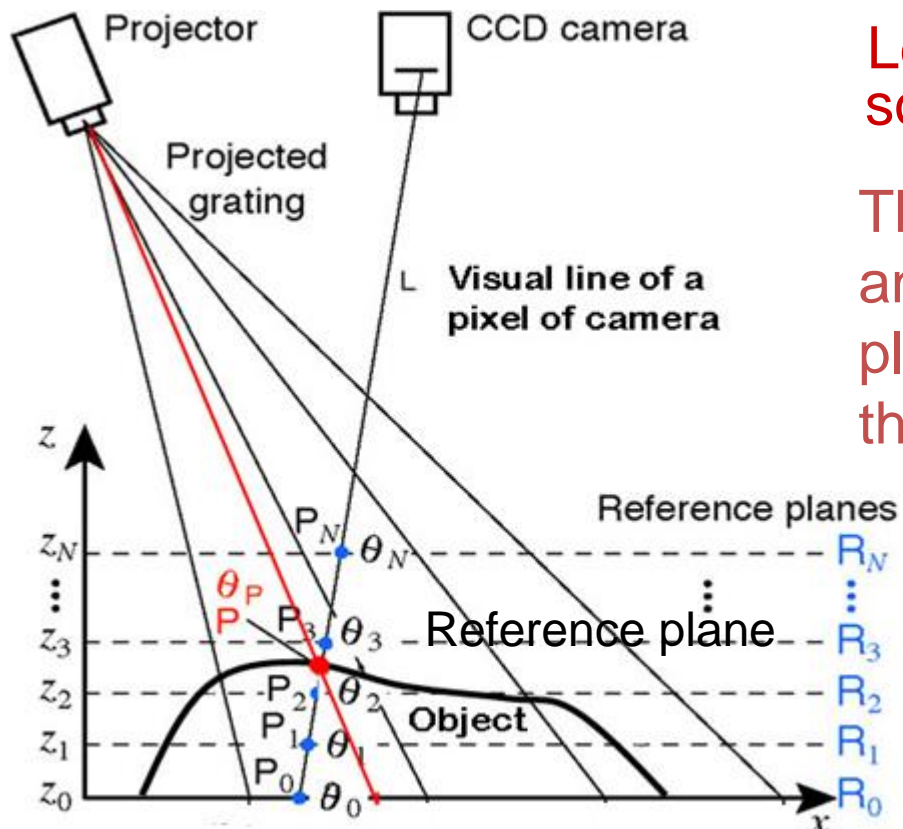
Whole-Space Tabulation Method (WSTM) for triangulation

The calculation of triangulation is time-consuming.

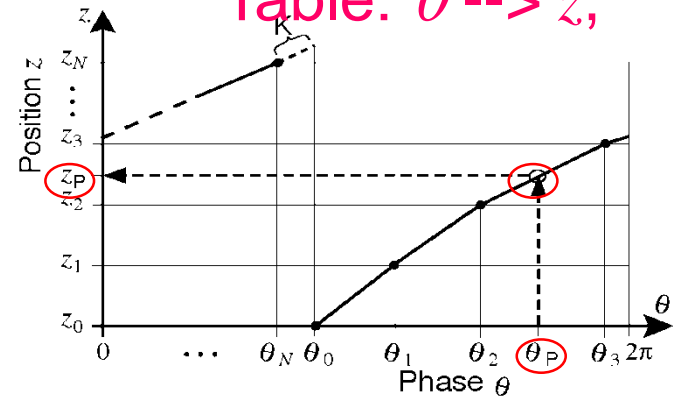
Lens, grating and image plane have some errors.

The correspondence among phase θ and z coordinate on each reference plane can be obtained at each pixel of the camera.

Table: $\theta \rightarrow z$,



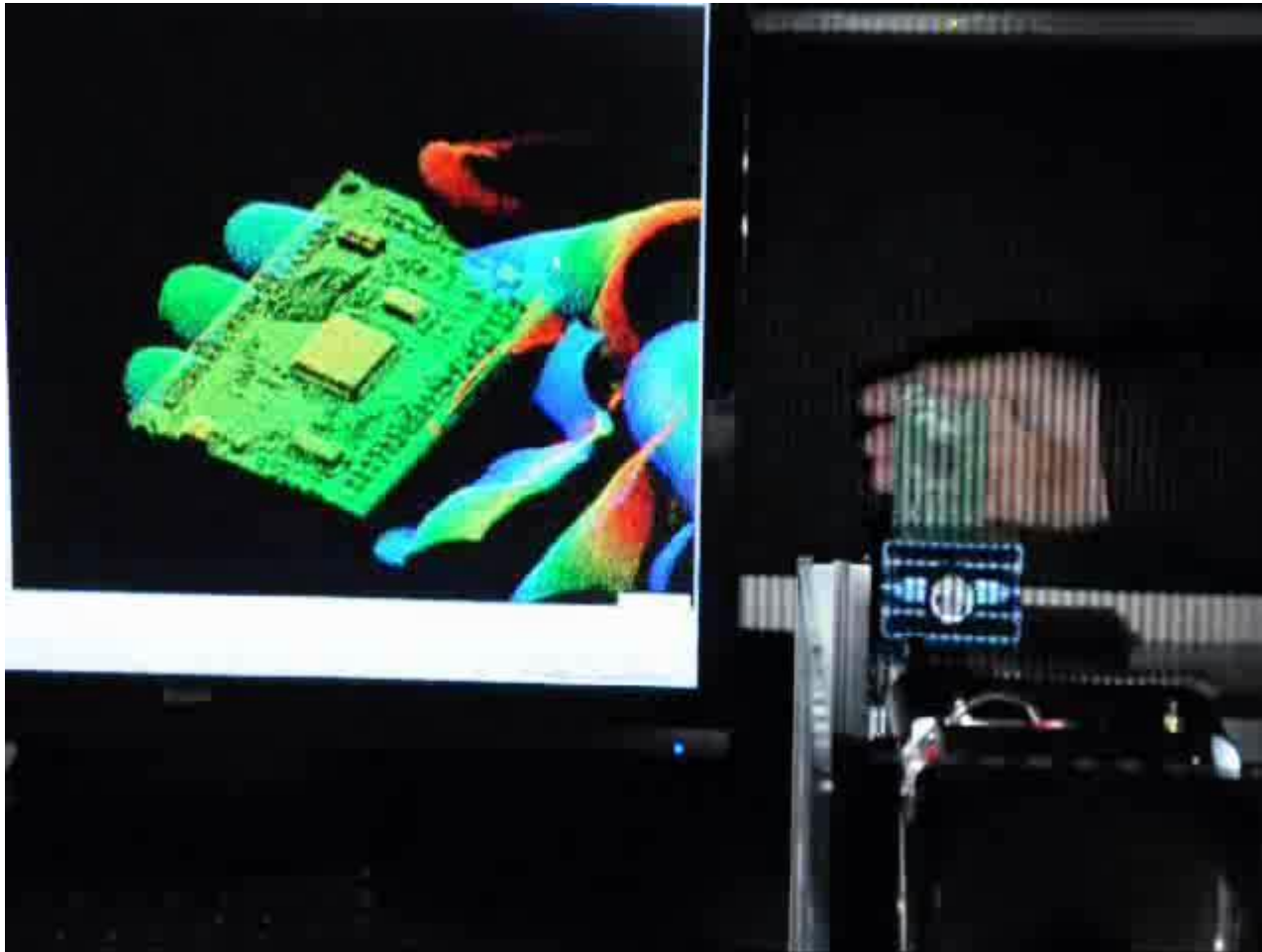
Triangulation optical system



No calculation: High speed

Automatic error cancellation: High accuracy

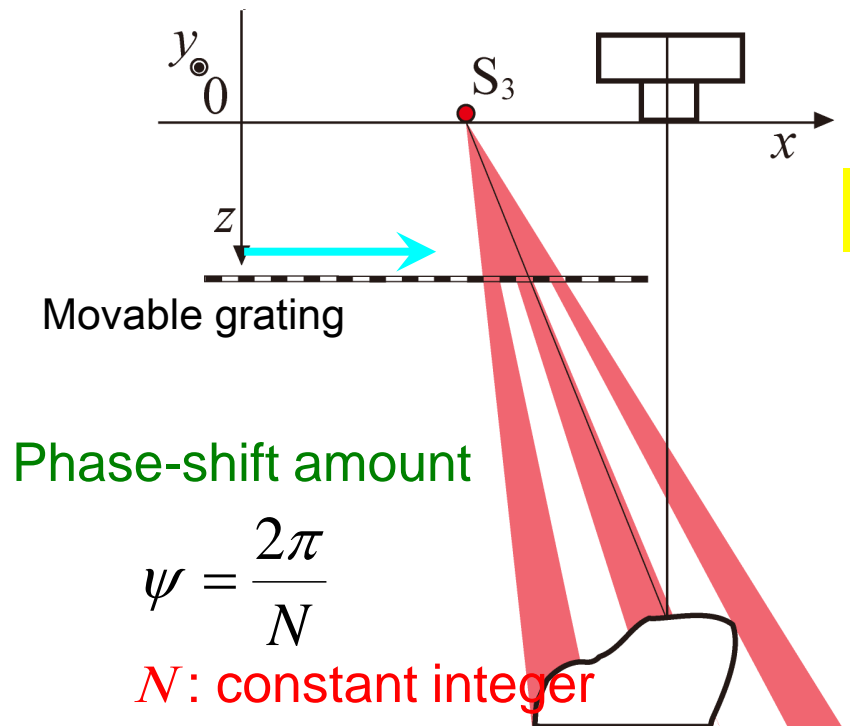
Examples of real-time shape measurements by whole space tabulation method



Light-source stepping method³²

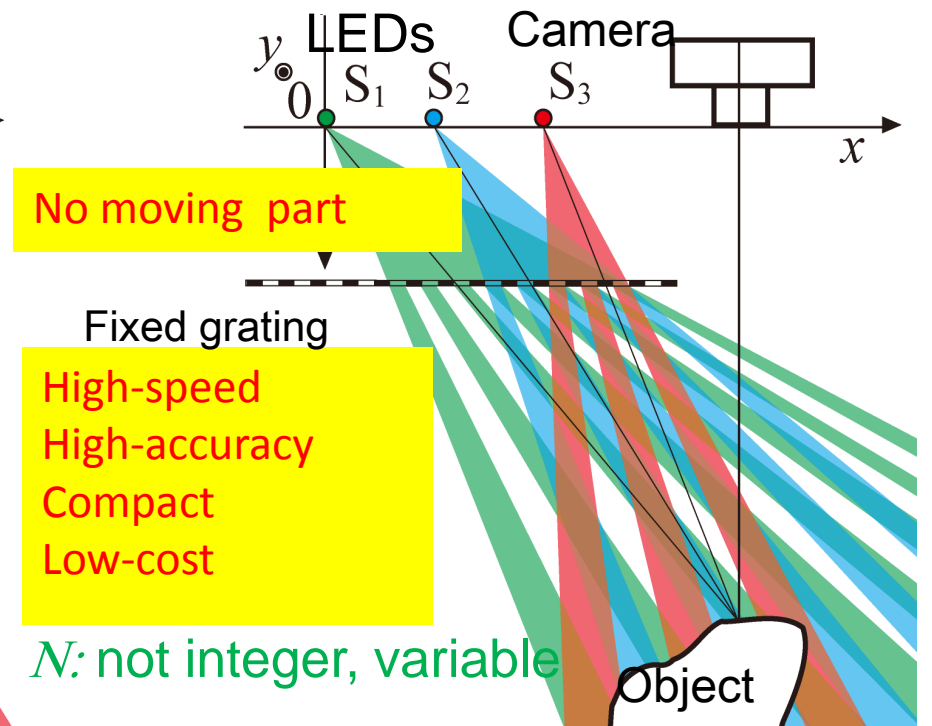
Conventional projector

Phase-shifting method
using single light source



Proposed projector using LEDs

Light-source-stepping method
using multi-light sources



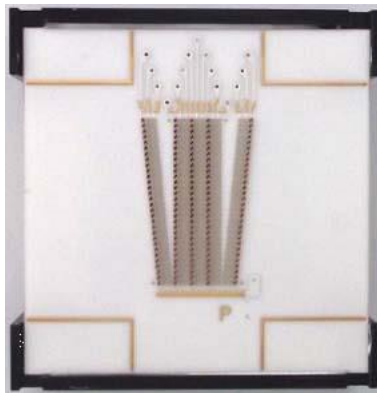
4D camera (Light-source-stepping)

33

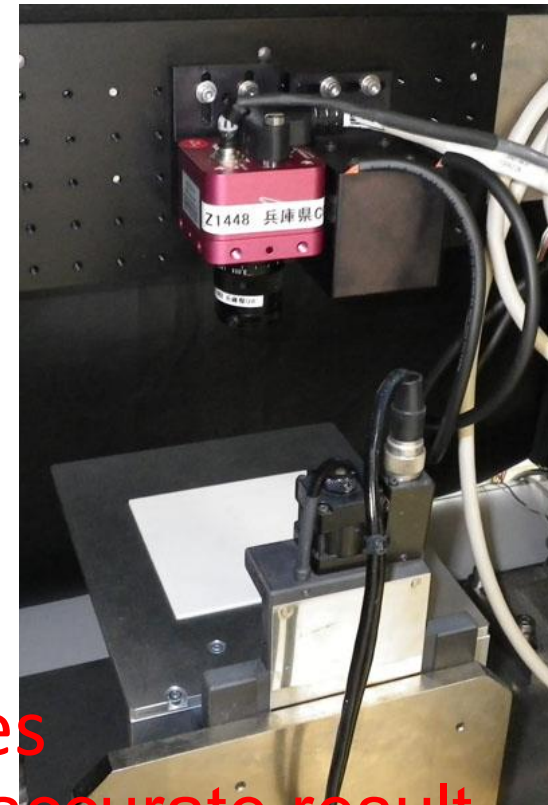
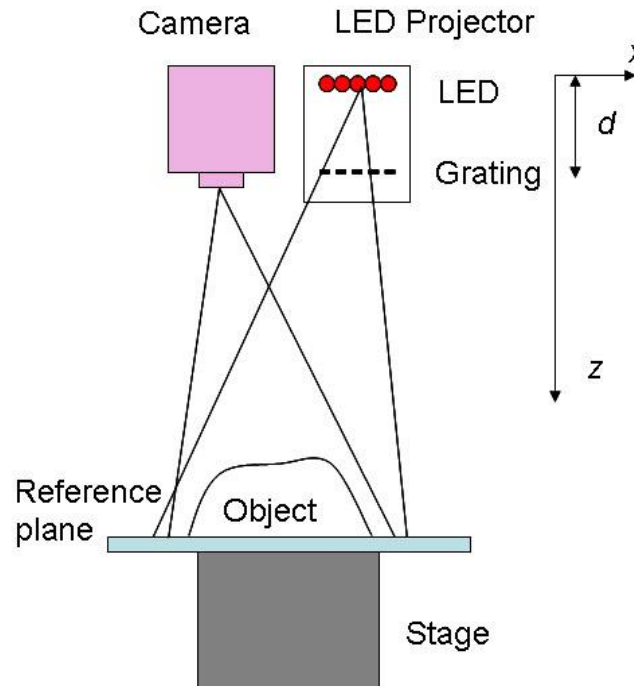
9-line for shape measurement

6-line for photograph recording

Each line has 30 chips with $350\mu\text{m}$ by $350\mu\text{m}$



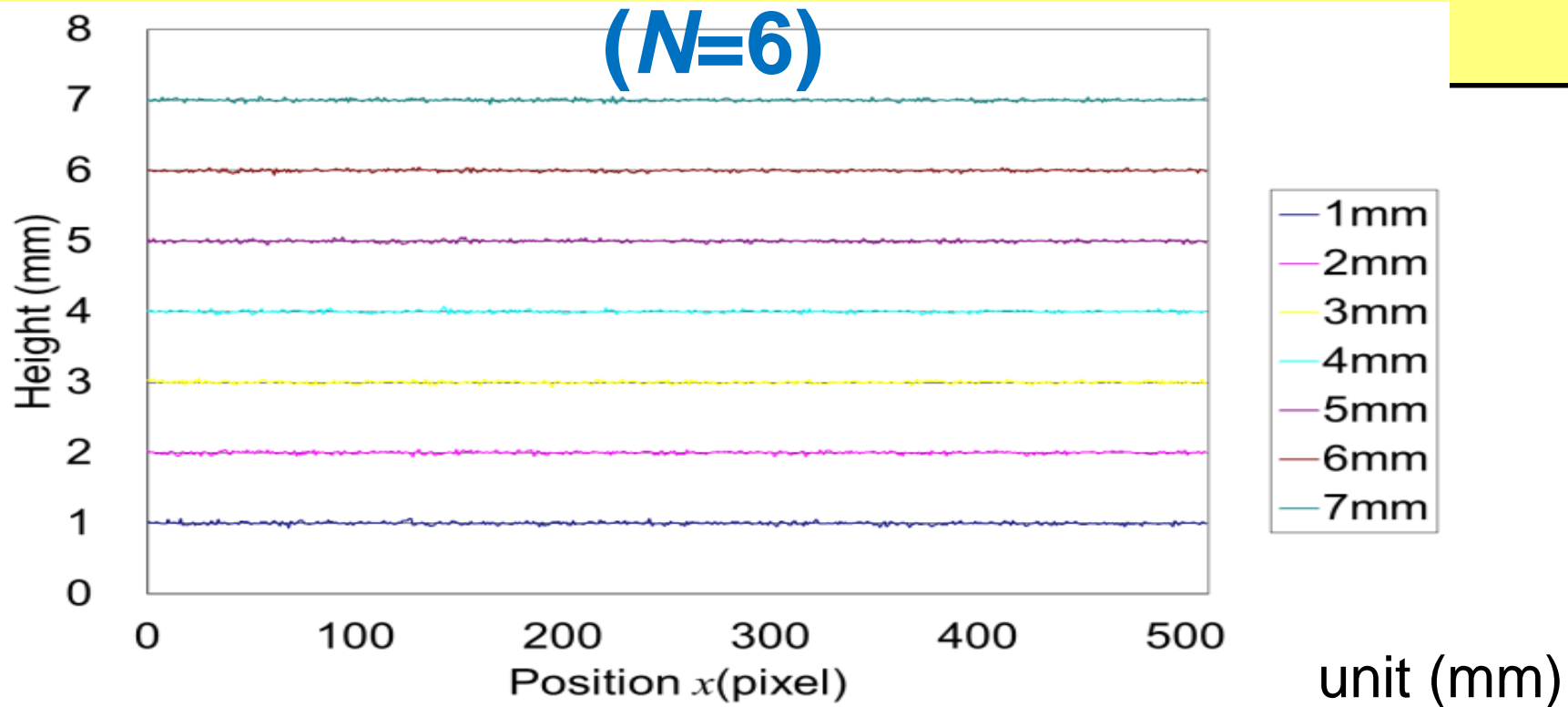
LED board



Use of original devices

Small size LED chip and small pitch for accurate result

Height measurement of flat plate

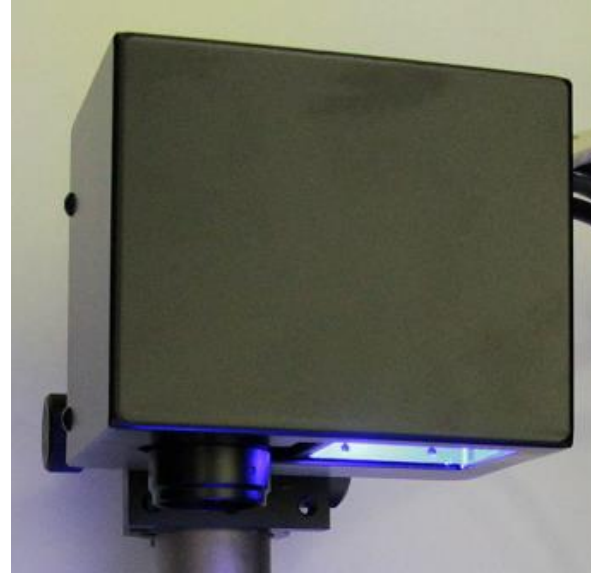
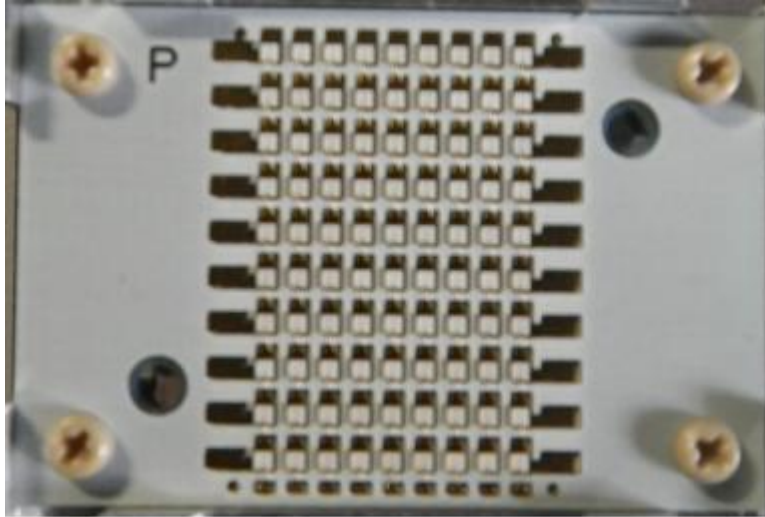


Height	1mm	2mm	3mm	4mm	5mm	6mm	7mm
Average	1.005	2.003	3.004	4.002	5.001	6.002	7.000
Error	0.005	0.003	0.004	0.002	0.001	0.002	0.000
Standard deviation	0.013	0.013	0.012	0.012	0.012	0.012	0.011

Accuracy : 13 μ m

Data of 500 pixels along a line

4D camera (using high-power LED for high-speed)

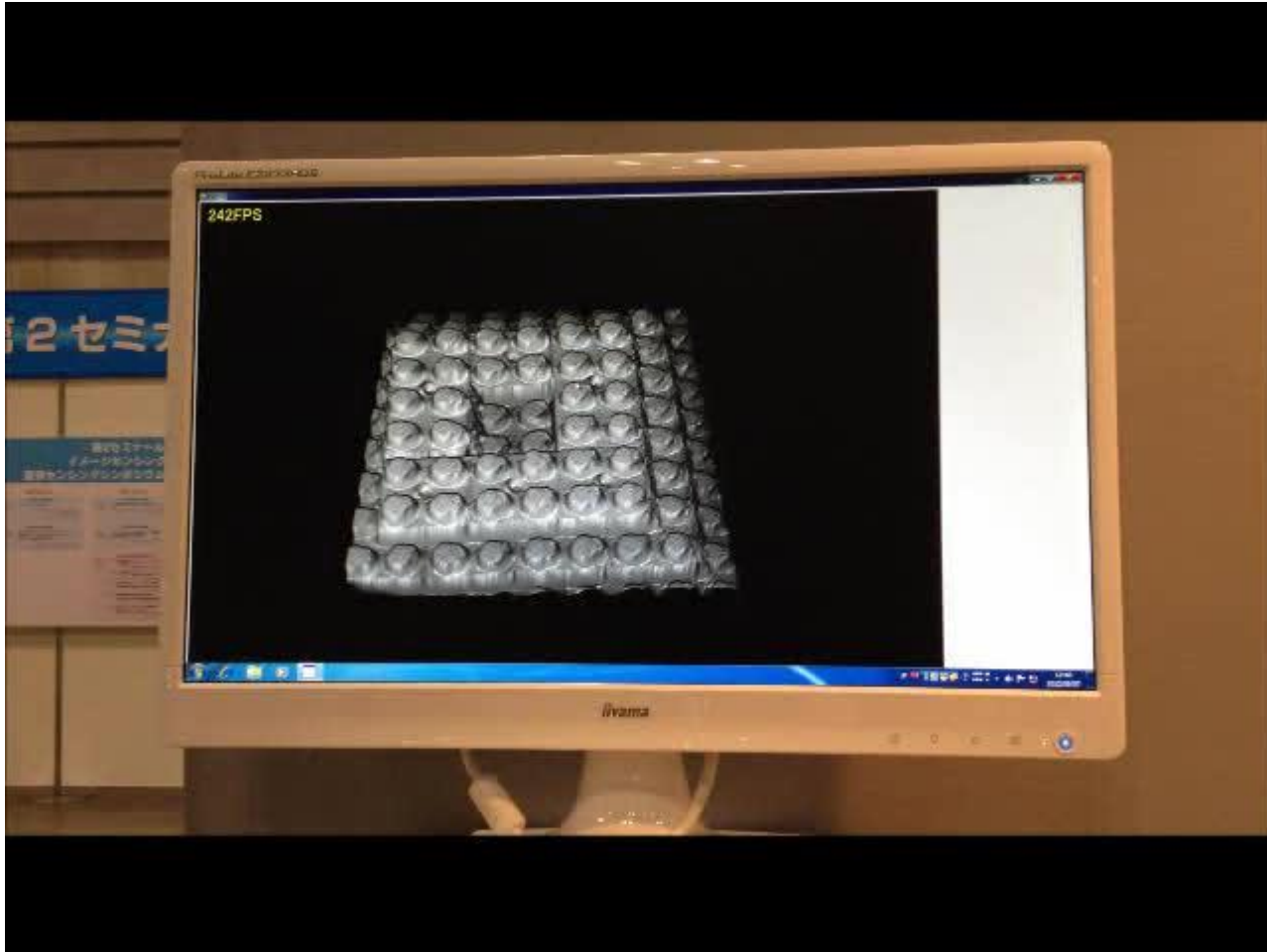


High power LED board

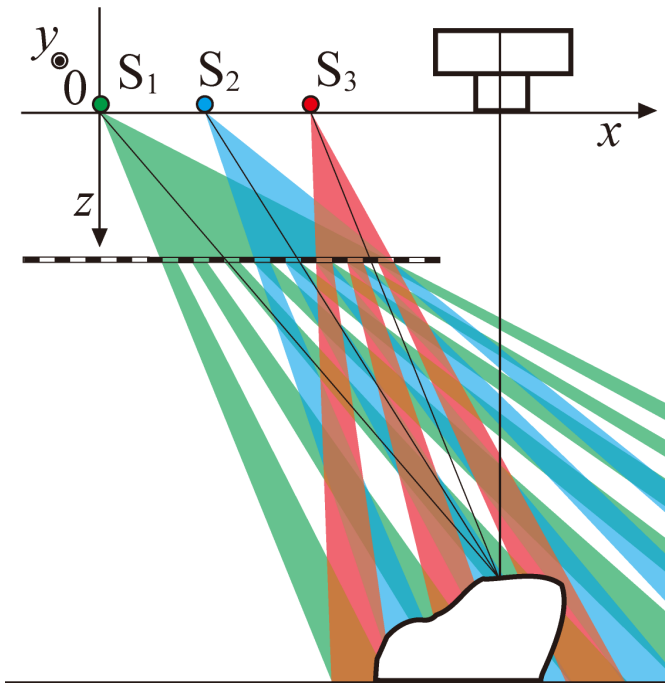
LED chip size	1mm × 1mm
Area size	100mm × 100mm × 25mm
Accuracy	0.04mm(σ)
Cycle time	0.08sec
Weight	Less than 1Kg



Real-time 3D shape measurement by³⁶ 4D camera at 230 fps



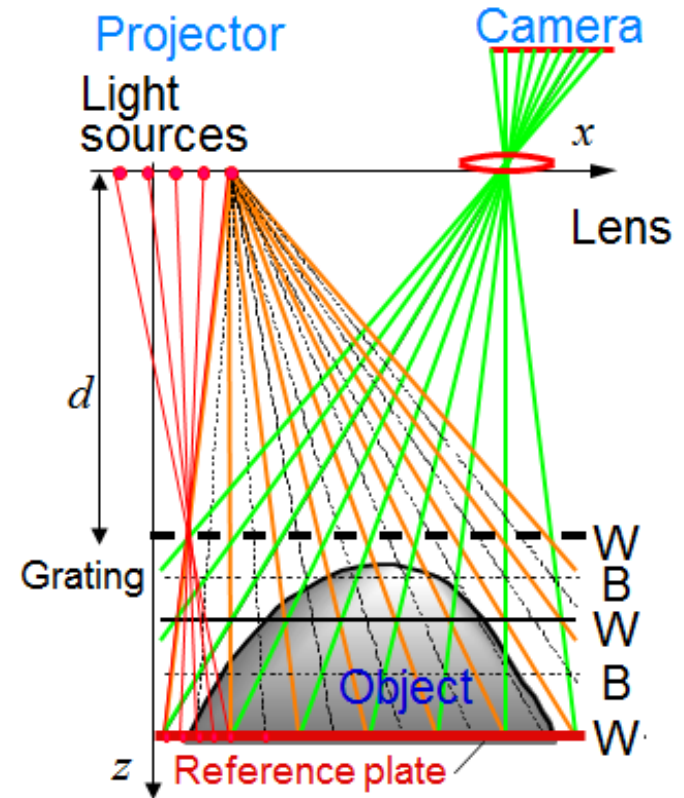
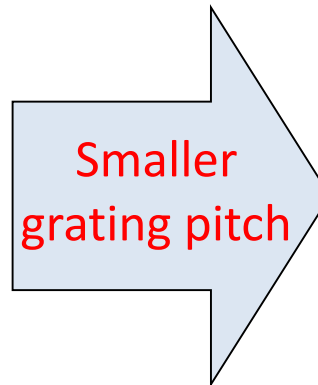
Light-source-stepping shadow moiré method



The pitch of a projected grating on an object is large.

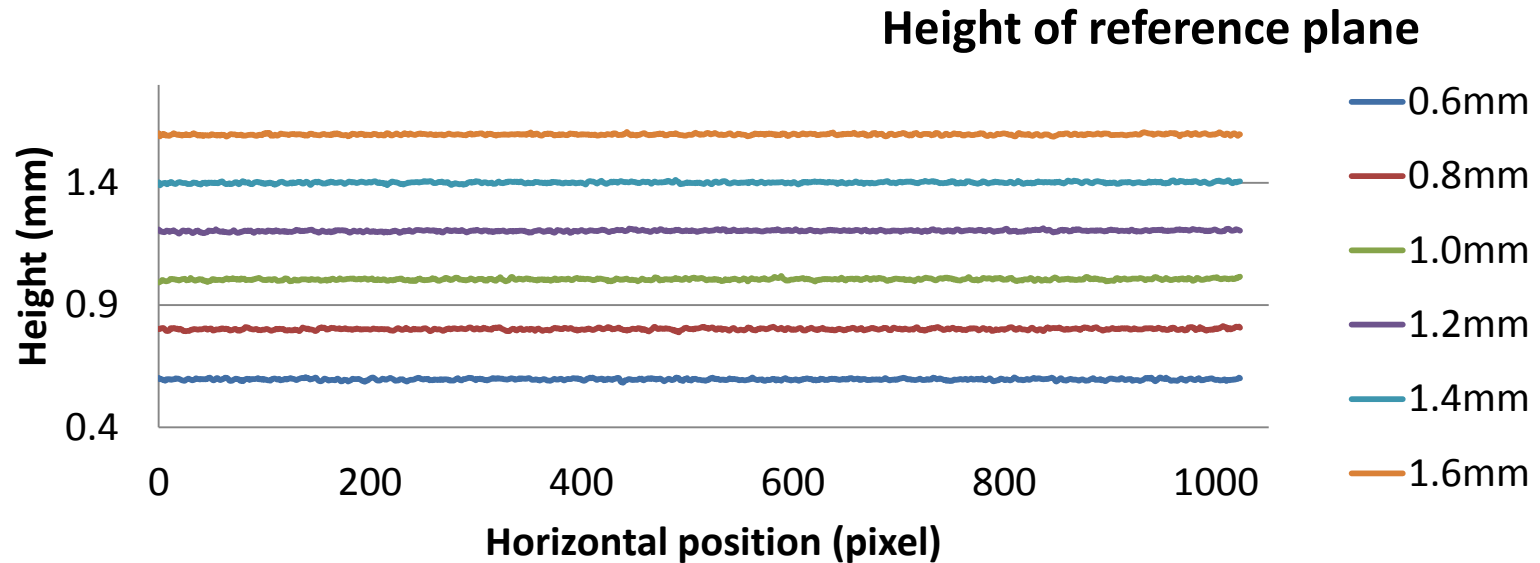
A moiré fringe pattern between the grating and the shadow of the grating is analyzed.

Light-source stepping method provides phase-shift easily and speedy.



Since a smaller pitch of a projected grating is used for shadow moiré, the accuracy is better.

Accuracy of shadow moiré camera ³⁸



(unit: mm)

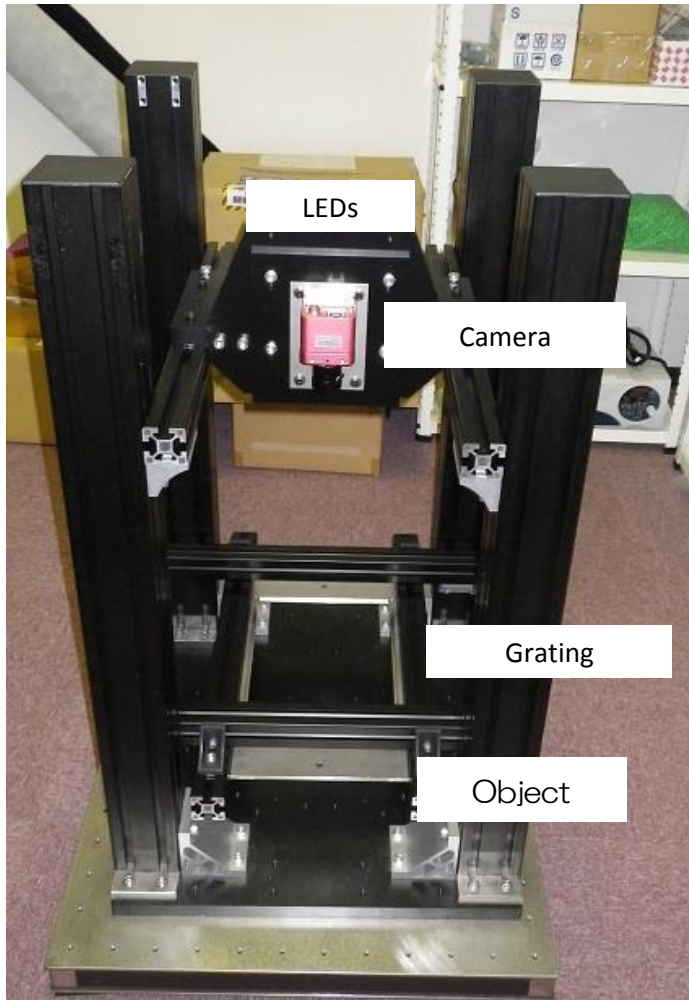
Position	0.6	0.8	1	1.2	1.4	1.6
Average	0.600	0.800	1.003	1.203	1.402	1.599
Error	0.000	0.000	0.003	0.003	0.002	-0.001
S.D. σ	0.003	0.003	0.003	0.003	0.003	0.003

Accuracy is $3\mu\text{m}$

Data : 100 by 100 pixels near center

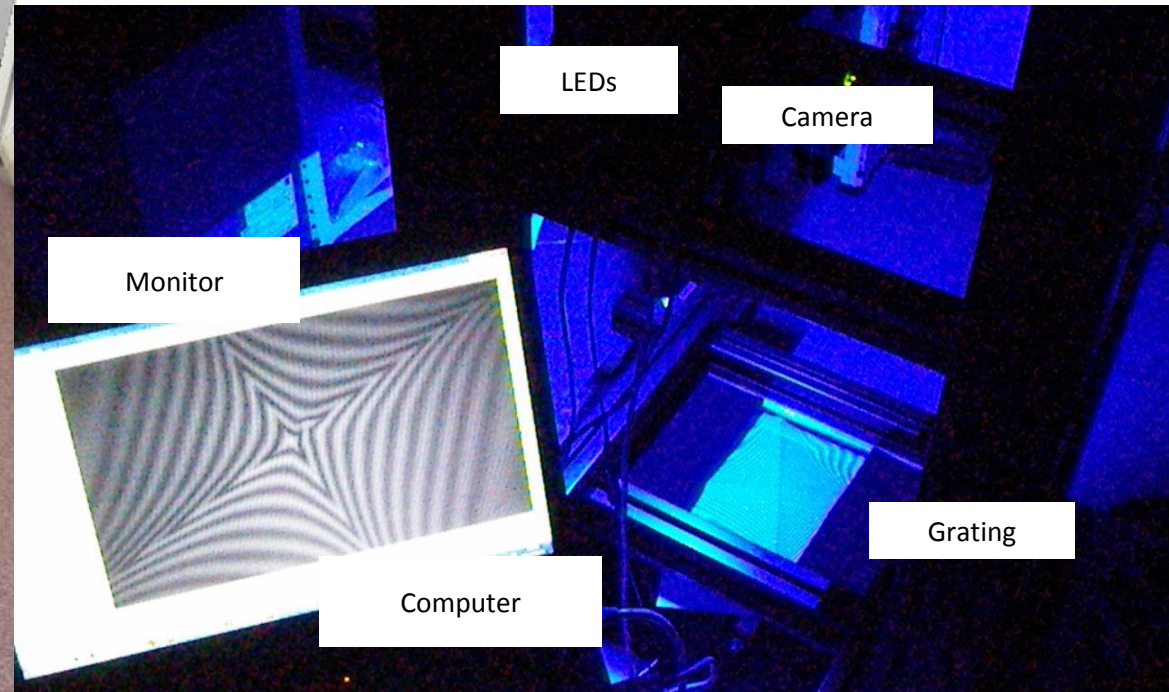
Shadow moiré camera

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Equipment

Display and equipment in working



Accurate small-pitch grating made by laser etching provides accurate result.

Application of Shadow moiré camera ⁴⁰



A grating with small pitch is put near the objects

Application to flatness measurement for electronic substrate

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Shadow Moiré Shape Measurement Device

Measurement Condition Setting

Measurement Image Input Image Phase Calculation Value Phase Graph Intensity Calculation Value Intensity Graph Height Measurement Value (Table) Height Measurement Value (Graph) Height Measurement Value (Formula) Height Measurement Value (Graph Formula)

Measurement Condition Setting

Measurement Base Plane (mm) Phase Shift Count
0.230 5

Stage Shift Pitch (mm) Interference Count
0.100 1000

Z Shift Count Scale [mm]
20 2

Grid Pitch (mm) Light Pitch (mm)
0.4 4

Light Source Height (mm) Light Lens Diameter (mm)
400 120

Table Data Save Folder
C:\Users\moire\Desktop\LabVIEW Program\Caldata(XGA2)

Measurement Result Save Folder Save Effective
C:\Users\moire\Desktop\LabVIEW Program

External Device Setting

COM Port (LED) COM Port (STAGE)
COM8 COM7

Stage Control Status

1st Axis Position 0
2nd Axis Position 0
Error Status
1st Axis Status
2nd Axis Status
System Reservation 0000
Busy

Start Status Origin Return

Cam Ready Calibration Interval Table Data Measurement Execution Standby End

Height θ Height ψ

Height θ profX

Height θ profY

Graph Scale MAX (mm) 1.8
Graph Scale MIN (mm) 0

Control Position Data Height Phase Overall Analysis Average Standard Deviation Variance Histogram Display

Control Position Data	Height	Phase	Overall Analysis	Average	Standard Deviation	Variance
	0.985	5.057	全体解析	0.274	0.336	0.113

Program is developed by LabVIEW

Application to flatness measurement for mobile phone

シヤドームアレ法形状計測装置

測定条件設定

測定基準面(mm) 7.000
 ステージ移動ピッチ(mm) 0.020
 Z移動回数 1
 格子ピッチ(mm) 0.4
 光源高さd(mm) 400
 露光時間(μsec) 2000

位相シフト回数 5
 補間数 20
 スケール[mm] 2
 光源ピッチ(mm) 4
 光源レンズ間v(mm) 120
 平滑化枚数 1

3x3x3フィルタ有効

テーブルデータ保存フォルダ
 C:\Users\%...%\シヤドームアレカメラ%\
 % caldata(2014-1-23)

測定結果保存フォルダ 保存有効
 C:\Users\%moire%\Desktop%\
 % LabVIEW Program

外部機器設定
 COMポート(LED) COMポート(N-STAGE)
 COM8 COM9

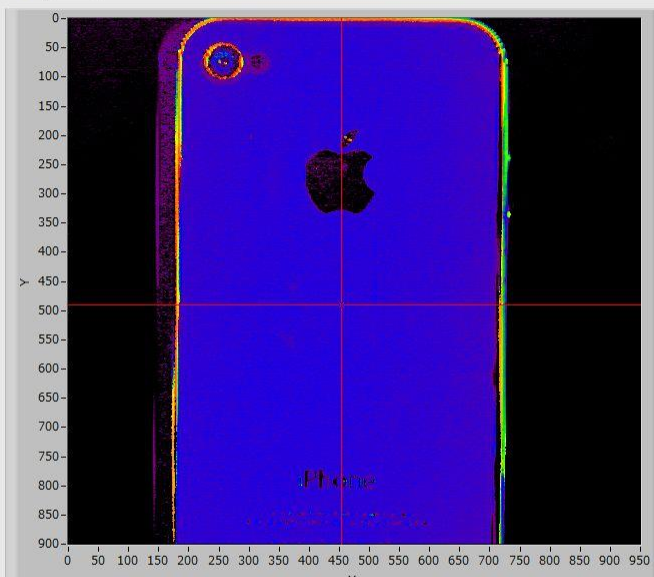
ステージ制御ステータス

1軸座標 9048
 2軸座標 0
 エラー状態 正常
 1軸状態 正常動作
 2軸状態 鈍無効
 システム予約 0000
 Busy

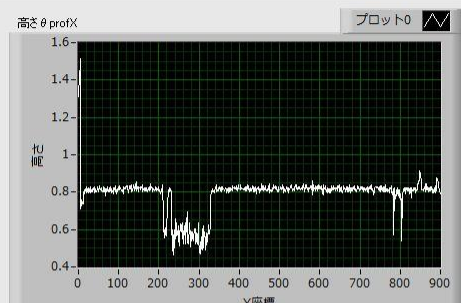
ステータス読み 原点復帰

測定画像 入力画像 位相計算値 位相グラフ 強度計算値 強度グラフ 高さ測定値(テーブル) 高さグラフ(テーブル) 高さ測定値(論理式) 高さグラフ(論理式)

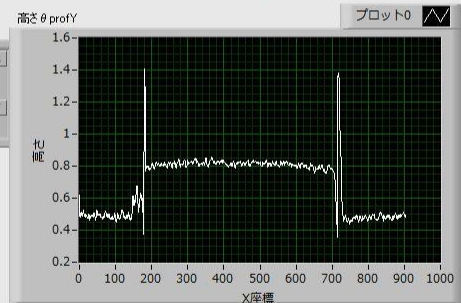
高さθ 高さψ



高さθ profX



高さθ profY



カーソル: X Y
 Cursor 0 453 490

グラフスケールMAX(mm) 1.6
 グラフスケールMIN(mm) 0.6

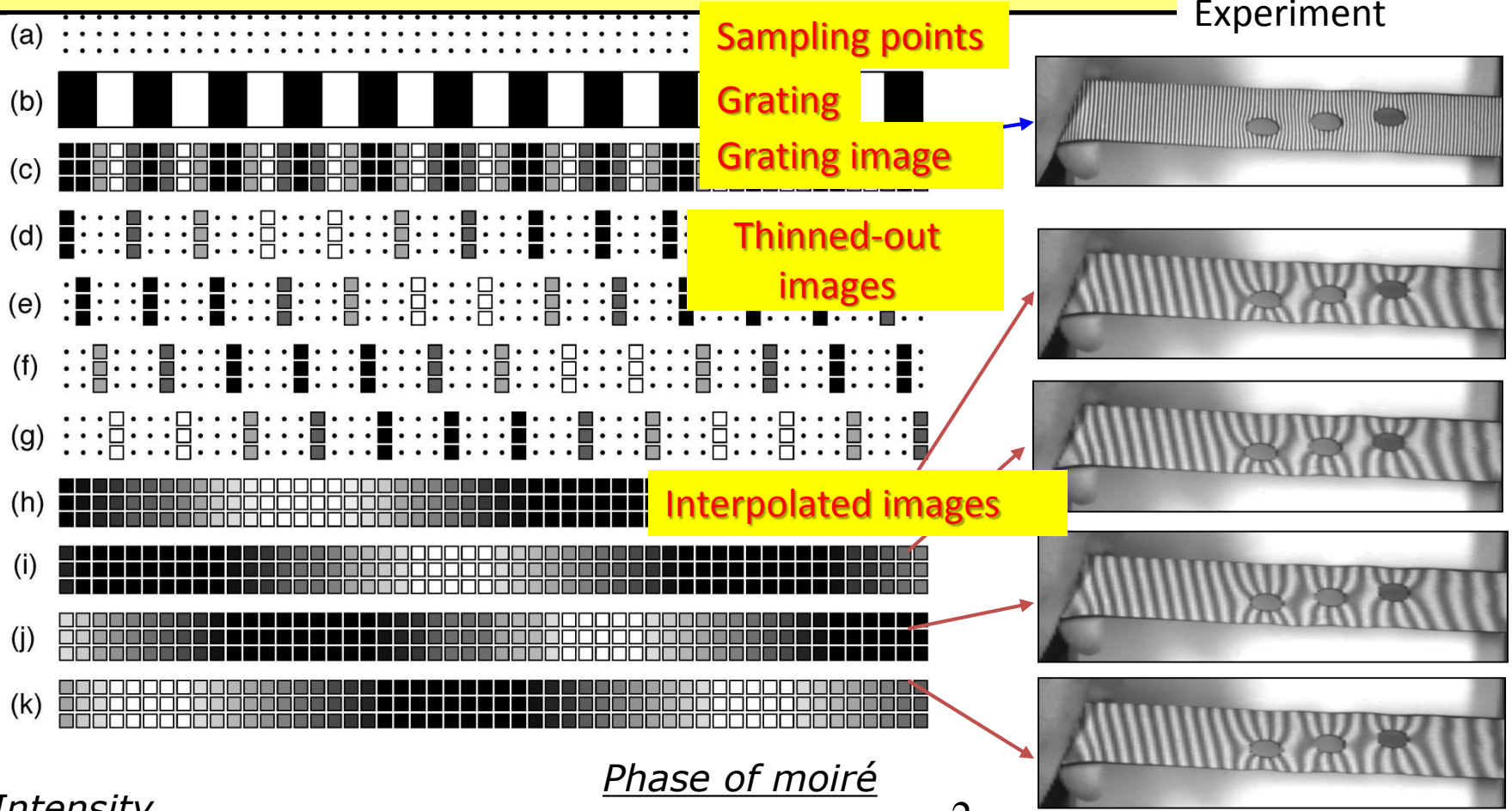
csv保存

ヒストグラム表示

測定fps 連続測定 0.63

高さ 0.819 位相 2.813 全体解析(中央100x100dot) 平均値 0.816 標準偏差 0.012 分散 0.000

Cam Ready キャリブレーション 空間テーブルデータ読み 測定実行 待機中 終了



Intensity

$$I_k(i,j) = I_a(i,j) \cos[\phi(i,j) + k \frac{2\pi}{N}] + I_b(i,j)$$

Phase of moiré

$$\tan \theta = - \frac{\sum_{n=0}^{N-1} I_n \sin(n \frac{2\pi}{N})}{\sum_{n=0}^{N-1} I_n \cos(n \frac{2\pi}{N})}$$

In sampling moiré method, phase is analyzed from one image.

S. Ri, M. Fujigaki, Y. Morimoto, *Exp. Mech.*, **50**, 501 (2010).

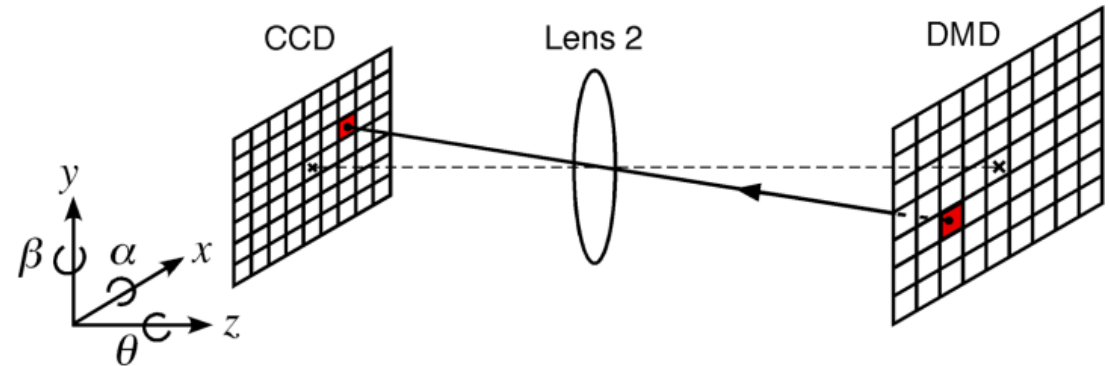
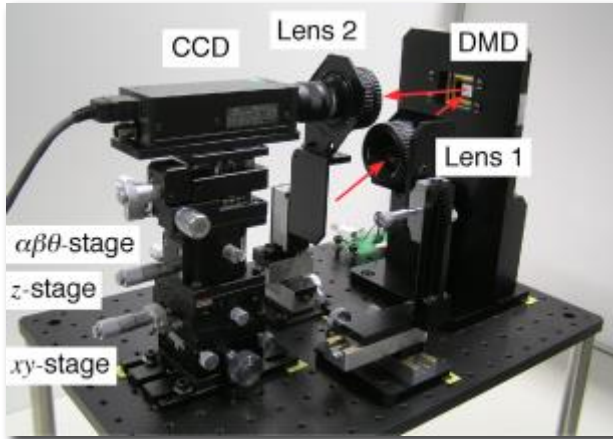
Each pixel of CCD Camera with individual shutter using DMD

[1] S. Ri, M. Fujigaki, T. Matui, Y. Morimoto, [SEM conf.](#), Portland, USA (2005)

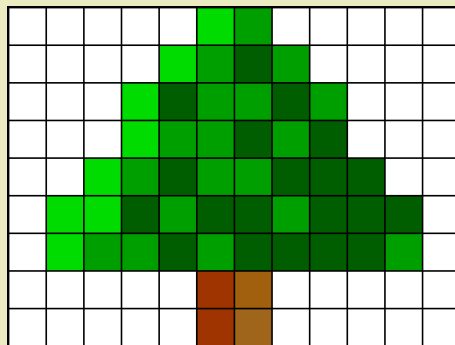
[2] S. Ri, M. Fujigaki, T. Matui, Y. Morimoto, [Experimental Mechanics](#), **46**, 67 (2006)

[4] S. Ri, M. Fujigaki, T. Matui, Y. Morimoto, [Applied Optics](#), **45**, 6940 (2006)

Set-up of DMD camera

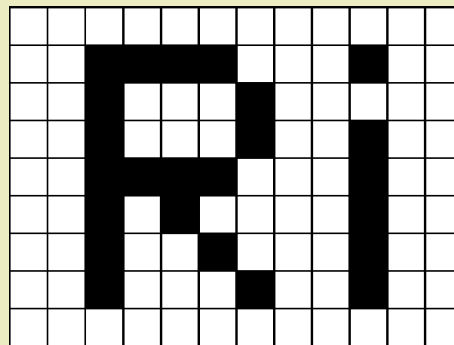


Illustration



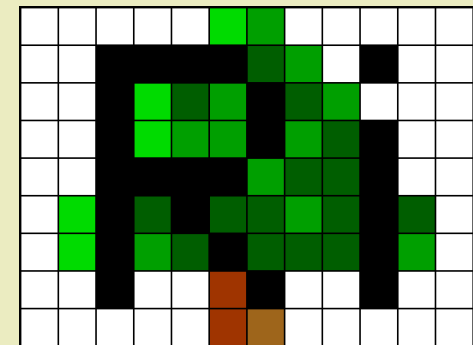
Object

+



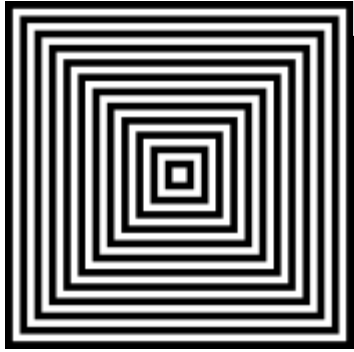
DMD "on/off" pattern

=

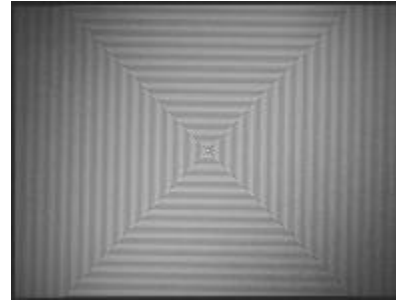


Captured image

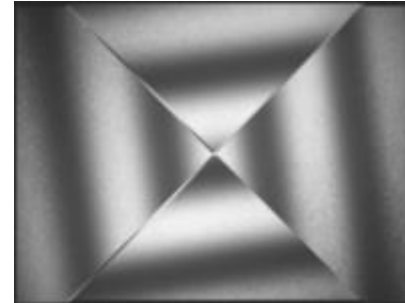
Adjustment of camera position to grating⁴⁵



Binary grating with
4-pixel pitch



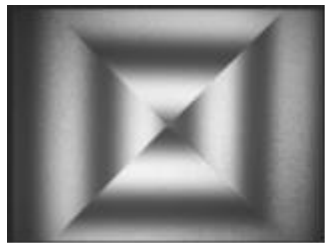
Grating image



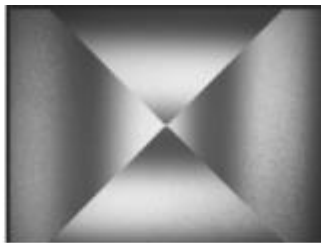
Moiré image



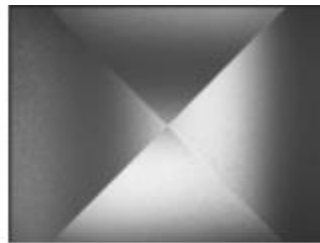
Phase of moiré



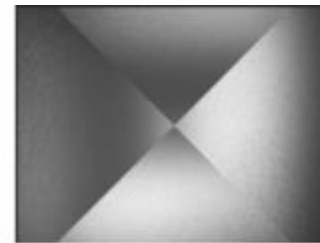
(a)



(b)



(c)



(d)



(e)



(f)



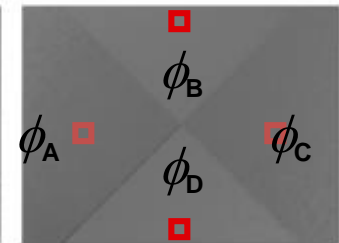
(g)



(h)



(i)



(j)

X-directional phase difference: $|\phi_A - \phi_C| = 0.061$, correspond to **1/25 pixels**.

Y-directional phase difference: $|\phi_B - \phi_D| = 0.043$, correspond to **1/37 pixels**.

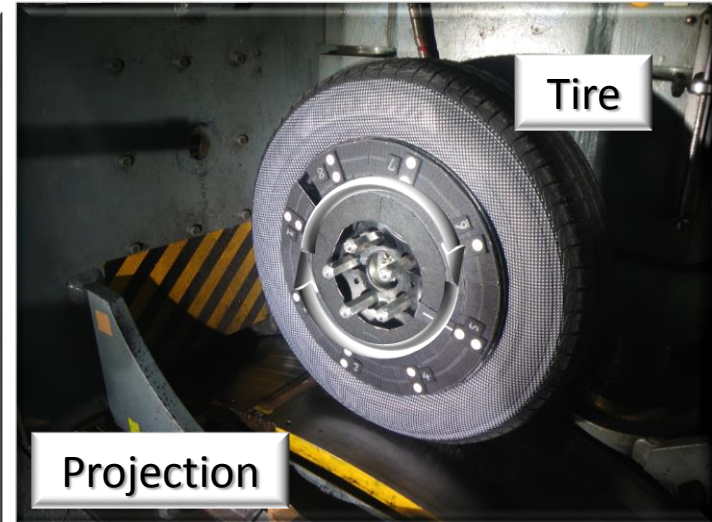
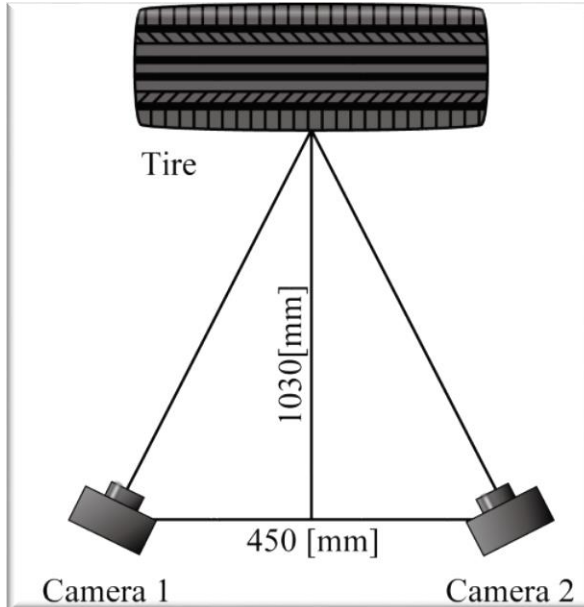
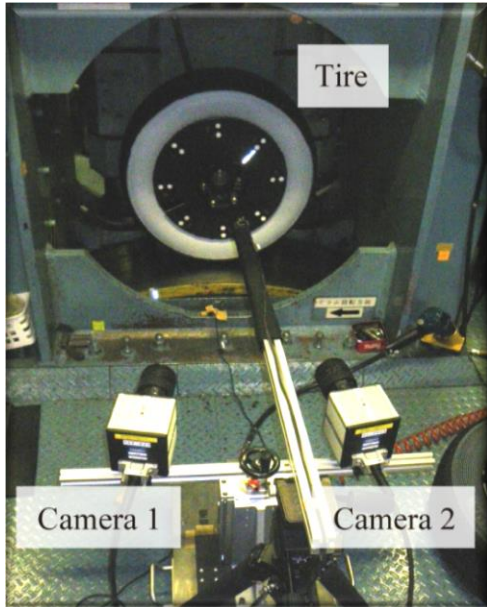
Prototype of High-speed Camera Switching System for 3D Shape and Strain Measurement

Motoharu FUJIGAKI, University of Fukui

Takaaki YOSHIKAWA, Wakayama University

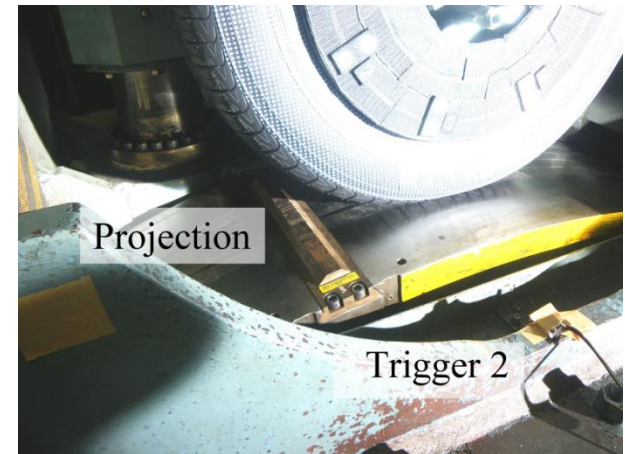
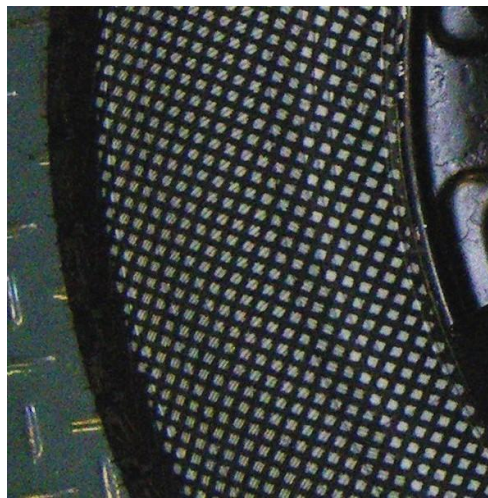
Yorinobu MURATA , Wakayama University

Dynamic strain distribution measurement



Two high-speed cameras and object

Frame rate: 1000 fps
Velocity of tire: 60 km/h



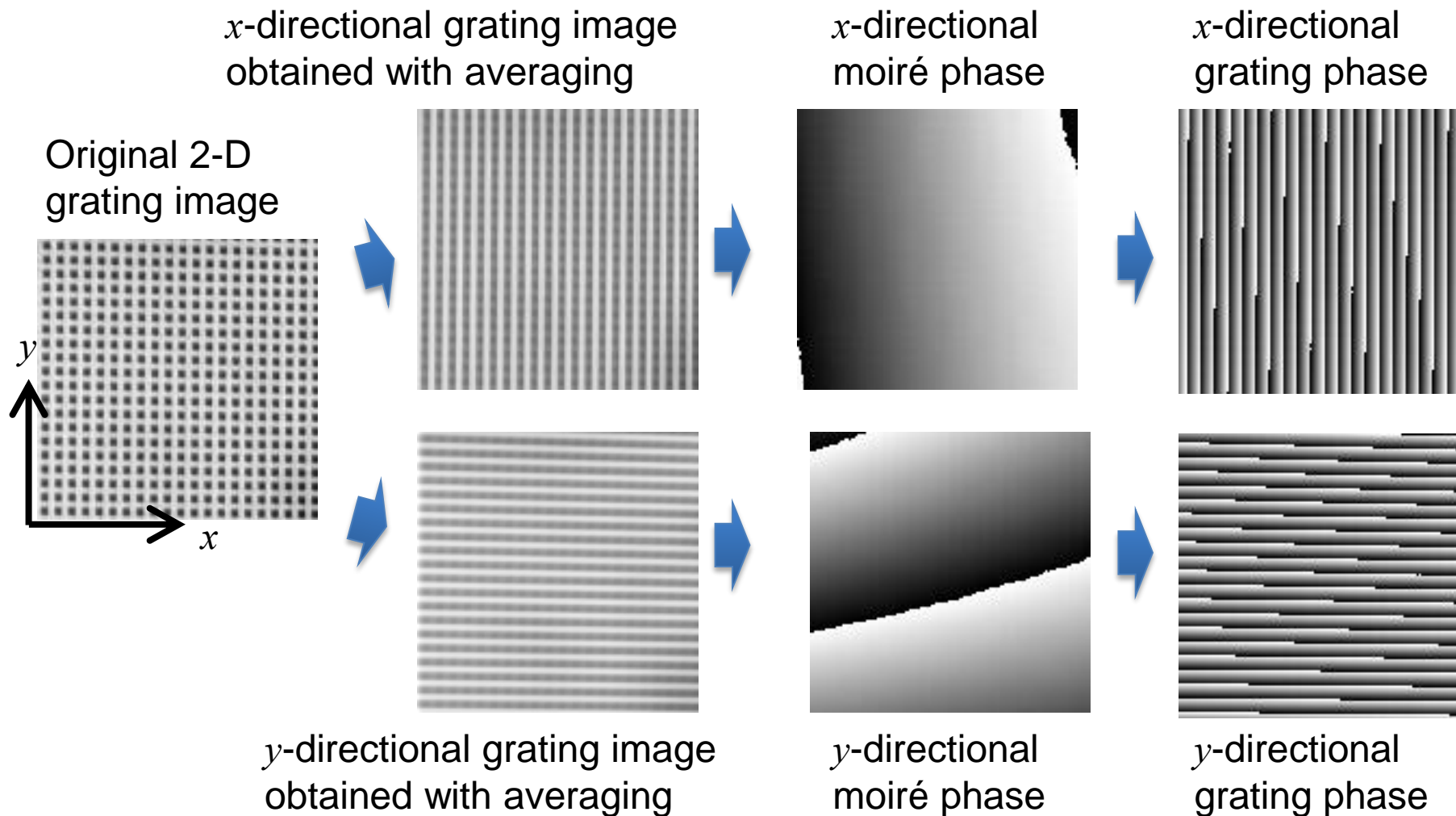
Tire treads a projection

2D-grating printed on the surface of tire

Experiment



2-D phase analysis by sampling moiré method



2-D phases analysis can be performed from a 2-D grating image.

Principle of shape and strain measurement (Stereoscopic method) 50

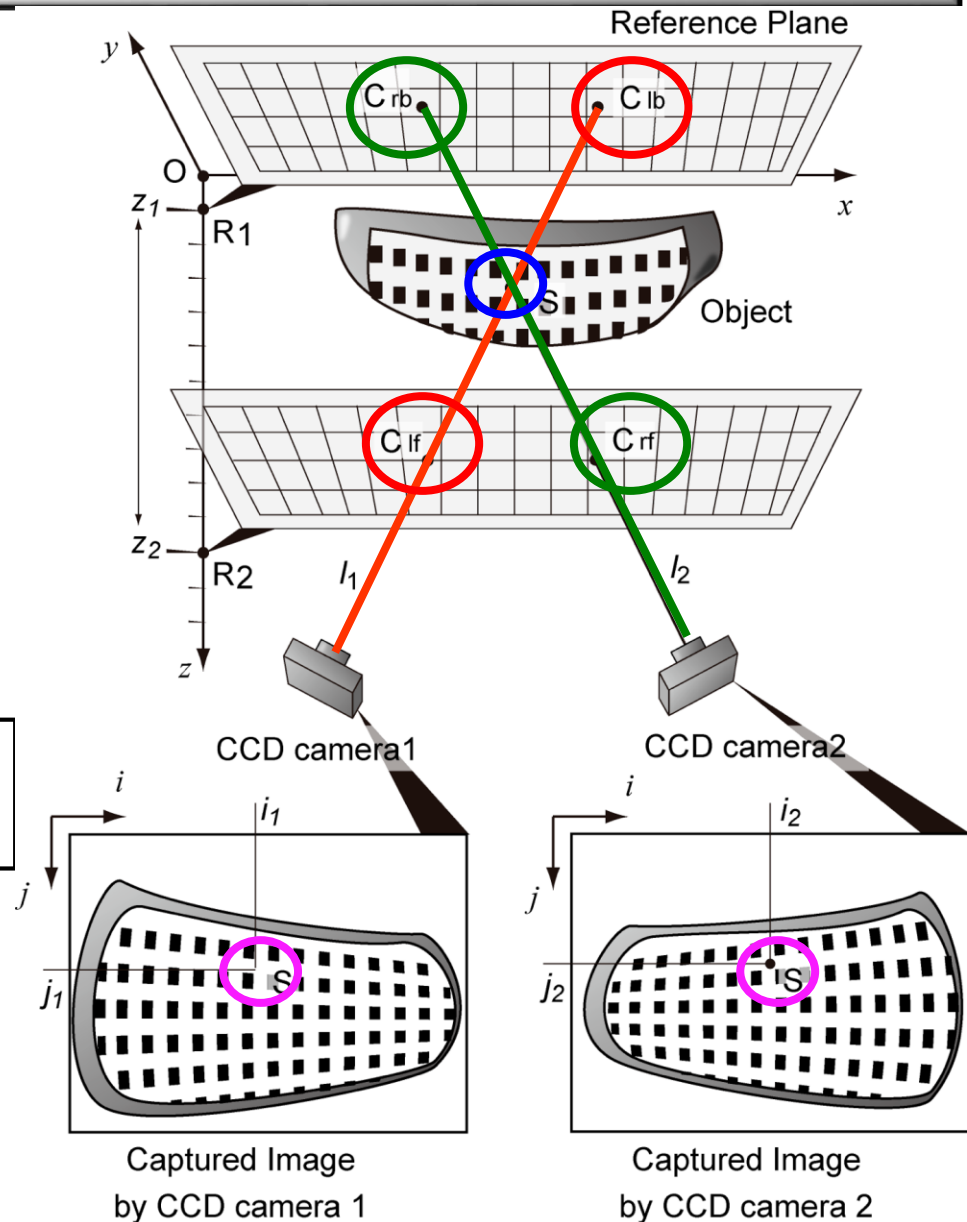
2-D grating images are taken by two cameras.

2-D phase is analyzed by **sampling moiré method**.

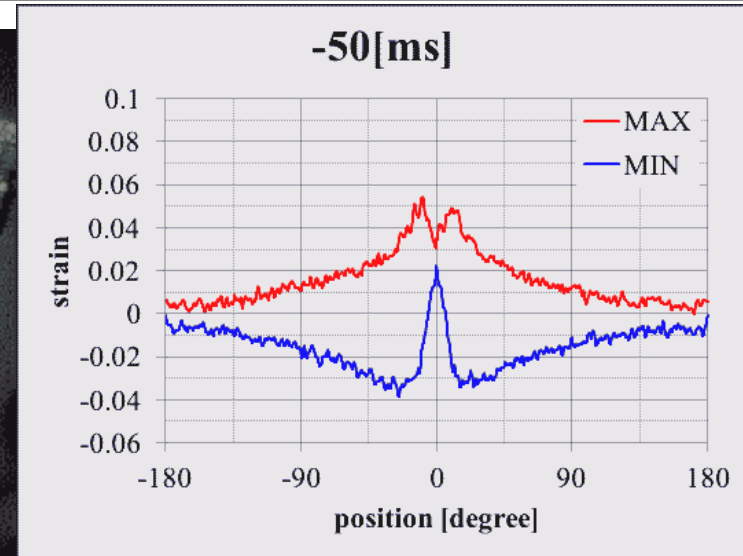
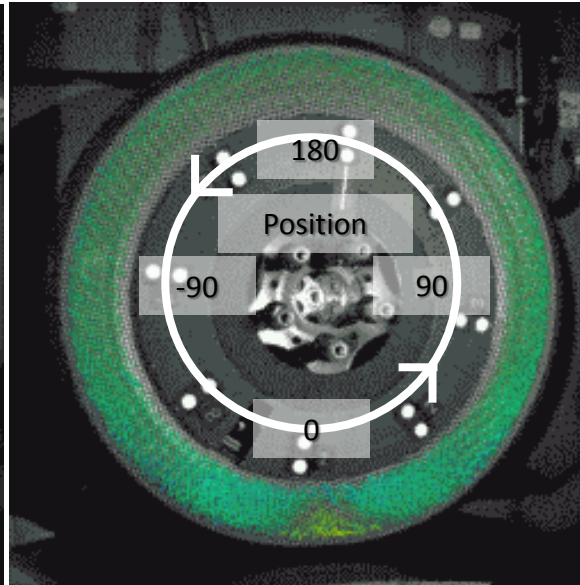
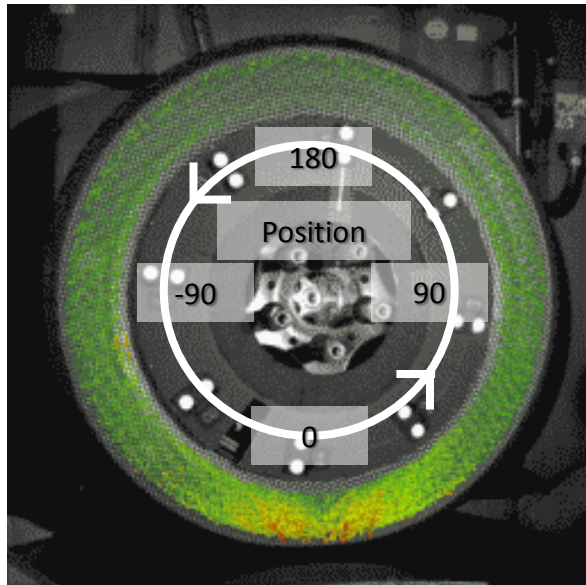
Corresponding pixels on each camera image are obtained from the 2-D phase.

Line l_1 and **line l_2** can be obtained from the corresponding pixels.


The 3-D coordinates of **point S** are obtained as the intersection of the two lines l_1 and l_2 .



Dynamic strain distribution measurement ⁵²



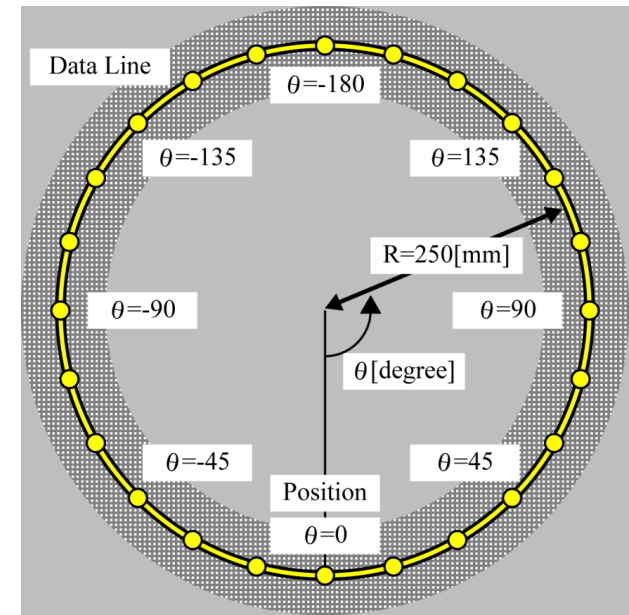
-0.10  0.10
Maximum principal
strain distribution

-0.10  0.10
Minimum principal
strain distribution

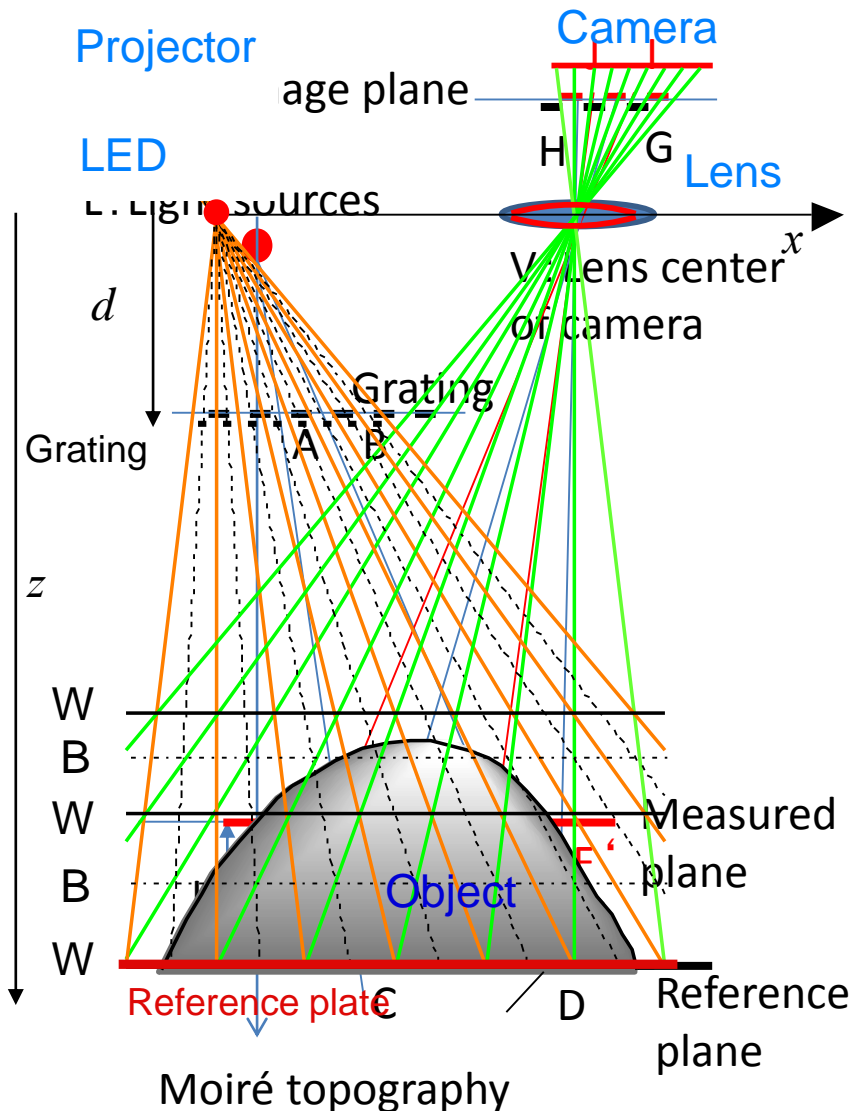
-50 ms
0 ms
+150 ms

↓
Tire treads a projection

Principal strain distribution



One-Pitch Phase Analysis (OPPA) Method⁵³ using sampling moiré method



The lens center is the same height of the LED light source from the reference plane.

The grating pitch on the camera CCD pixels is constant at any height.

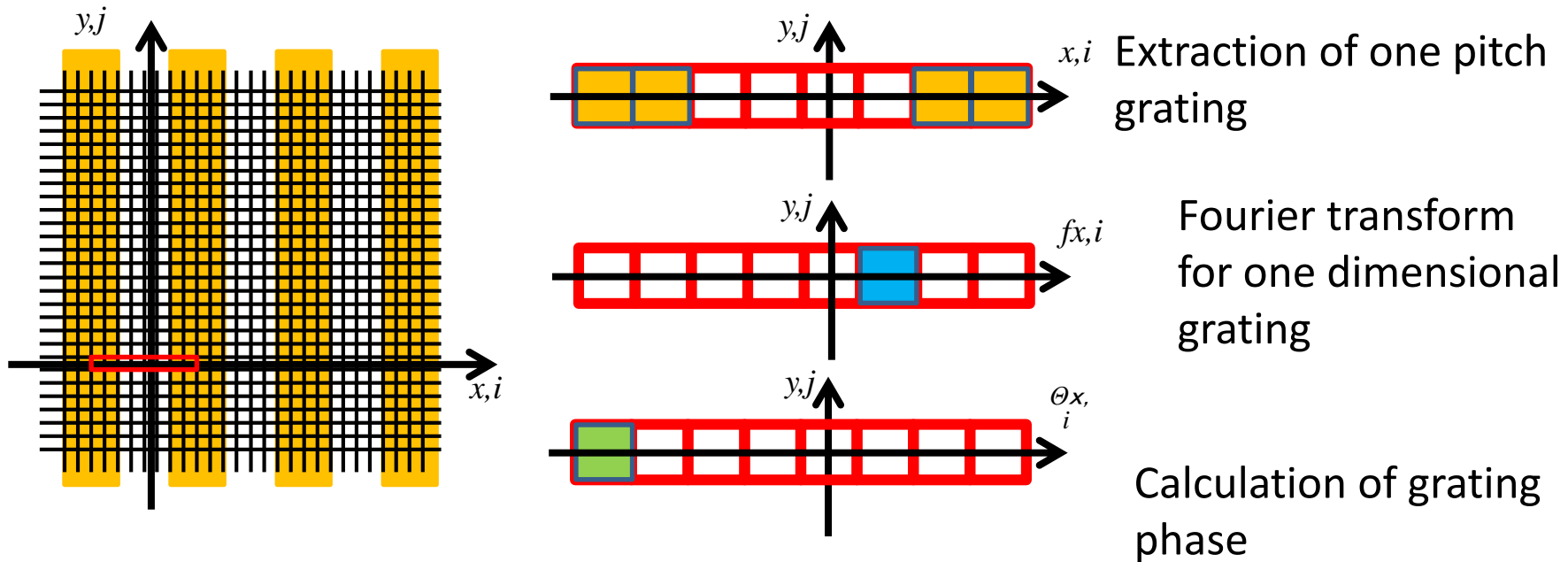
Only the phase of the grating is changed according to the height.

If N pixels are adjusted for one pitch of the grating, N pixels for one pitch is kept at any height.

Only the phase is different according to the height.

One dimensional grating projection

Phase analysis by sampling moiré



That is, phase is obtained from N pixel data as follows

$$\tan \theta = -\frac{\sum_{n=0}^{N-1} I_n \sin(n \frac{2\pi}{N})}{\sum_{n=0}^{N-1} I_n \cos(n \frac{2\pi}{N})}$$

Application to modal analysis of⁵⁵ vibrating plane (Optical system)

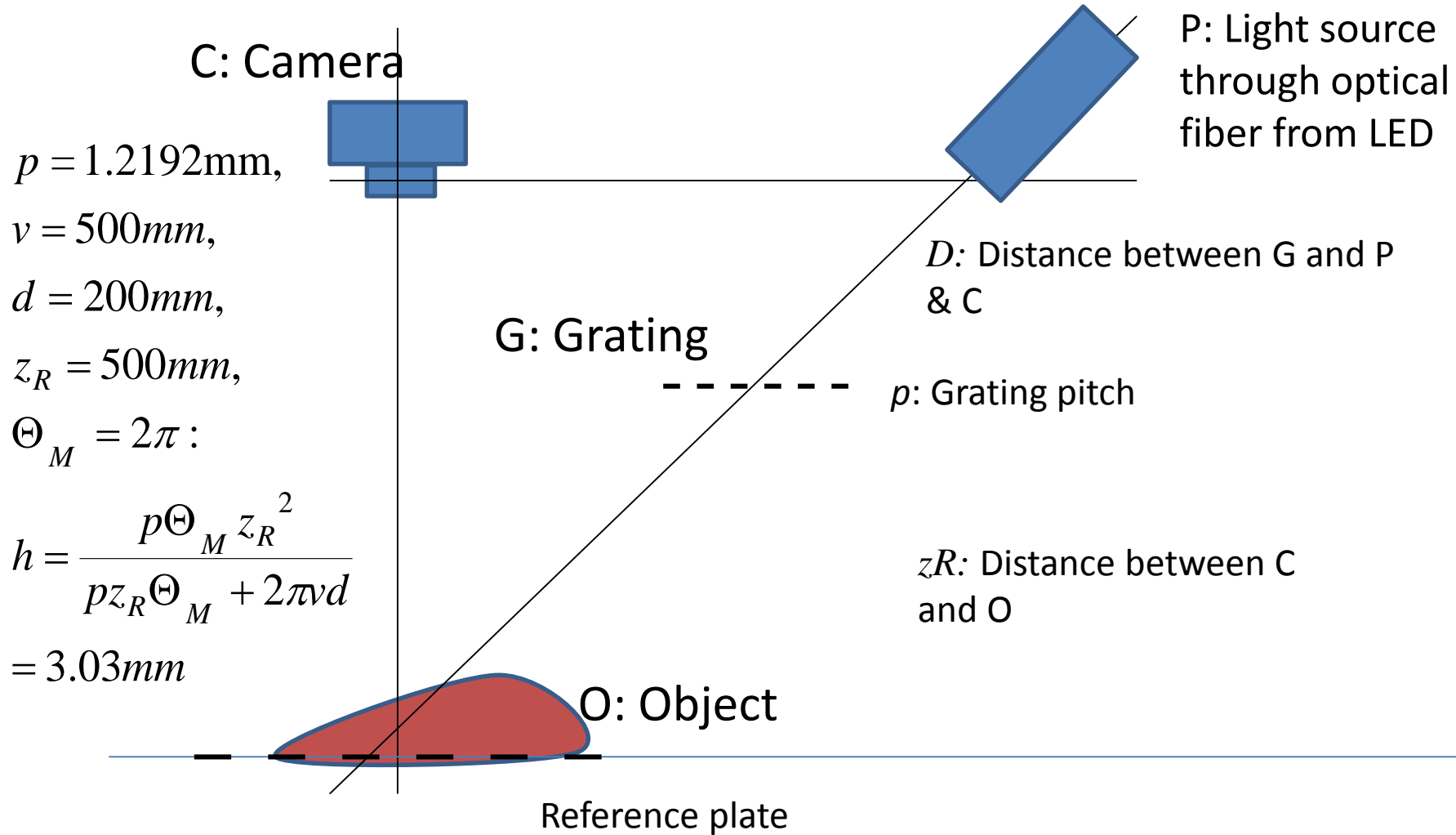
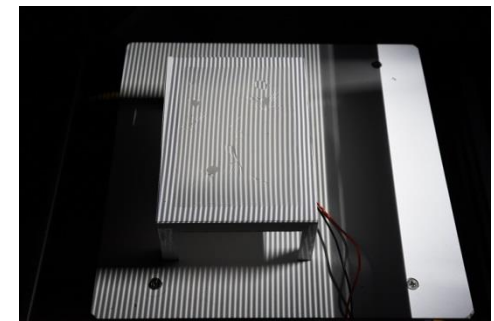
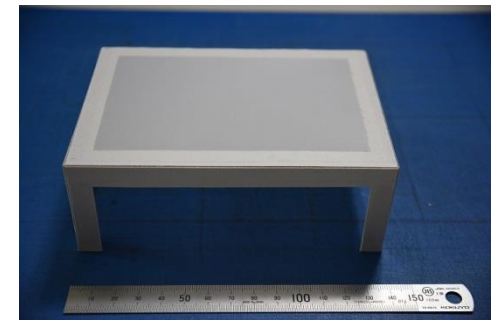
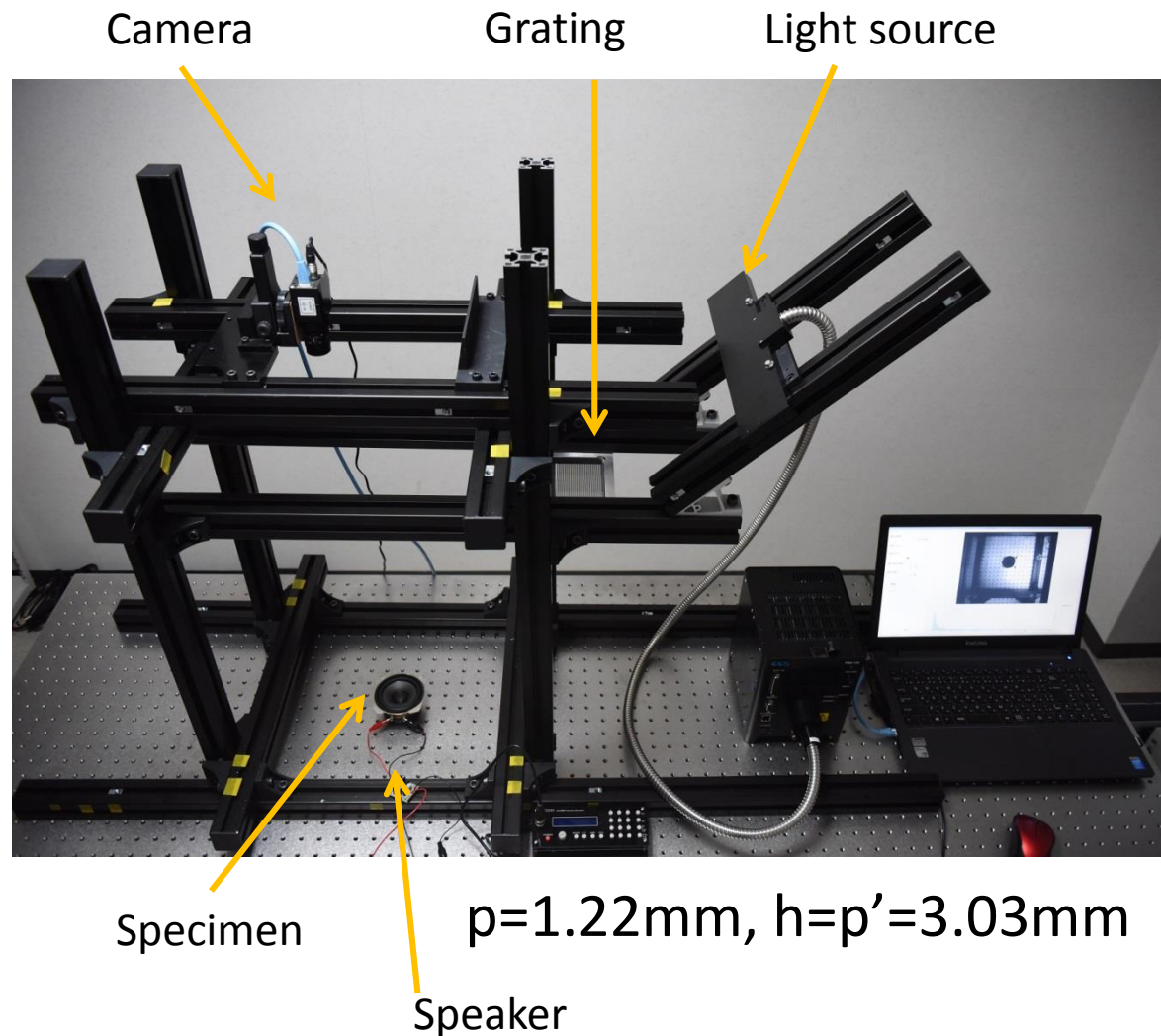


Photo of experimental system

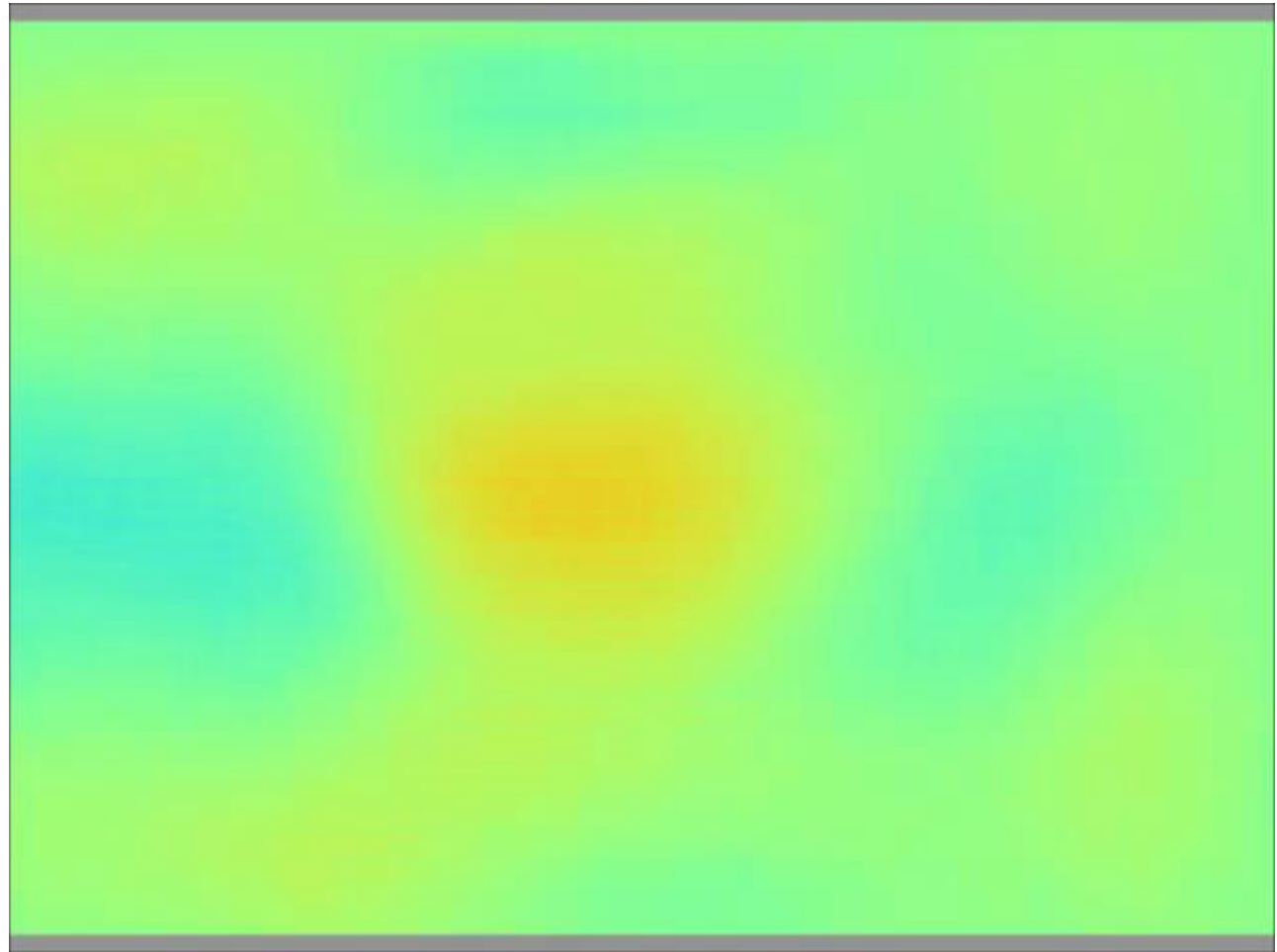


Vibration mode change according ⁵⁷ to frequency

Height
distribution
when
frequency
changes 27Hz
~37Hz
at 200 fps

Recording
speed:
200 fps

Pixel size :
320 × 240
pixels



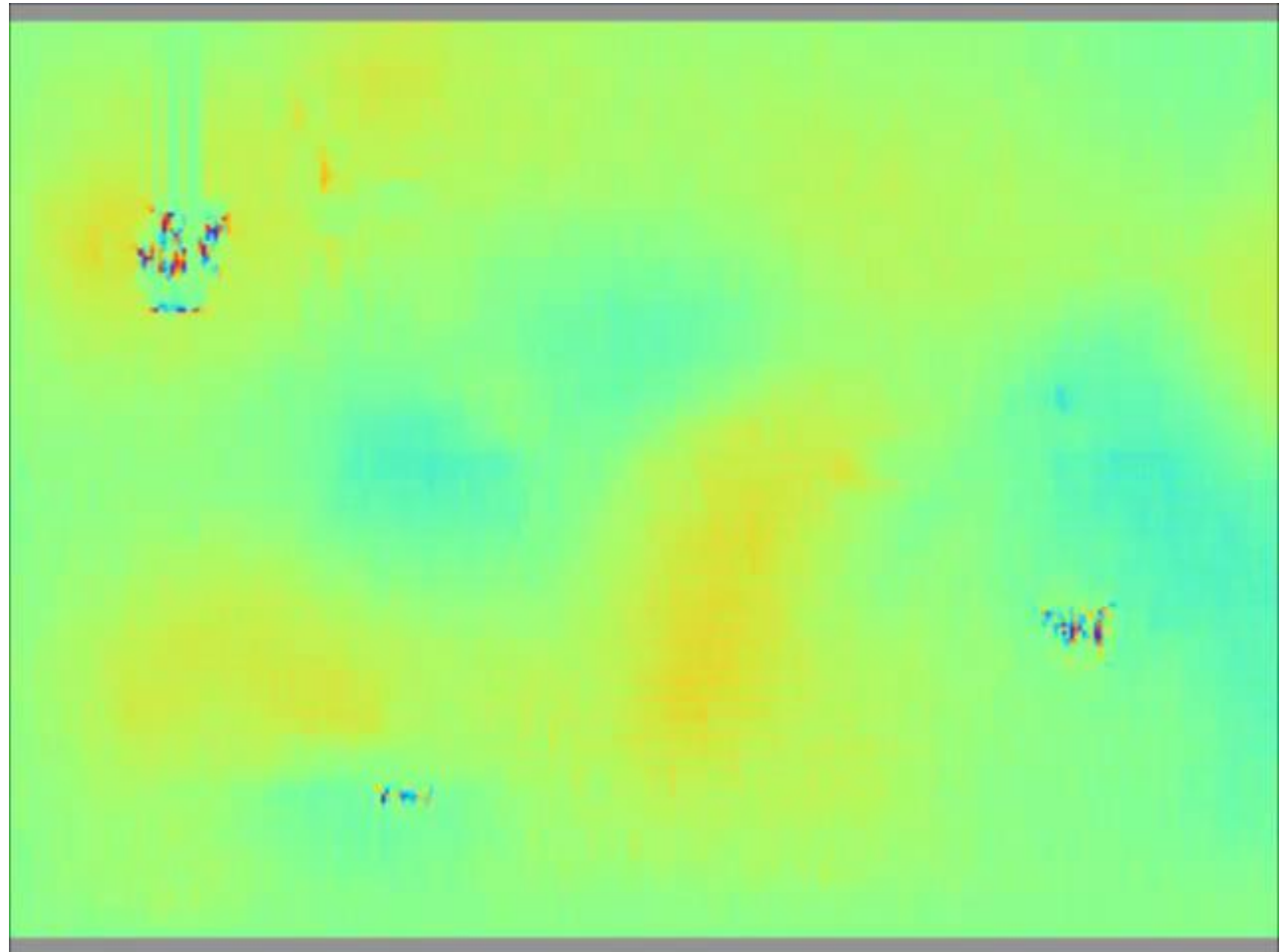
Slow motion movie

Modal analysis of vibrating rubber plate with defects 58

Height distribution when frequency changes 27Hz ~37Hz at 200 fps

Recording speed: 200 fps

Pixel size : 320 × 240 pixels



Features of SMM and OPPA

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Merit

- Moving object analysis because of use of only one image
- Less thermal error because of one-line light source
- No controller for light source because of no switching
- Simple system

Demerit

- A little bad spatial resolution
- Less resolution for object with different pattern in one pitch

Conclusions

- ◆ Moiré methods are useful to analyze full-field displacement, strain and shape.
- ◆ New moiré methods such as sampling moiré method and OPPA method are proposed to analyze dynamic shape, displacement and strain.
- ◆ They are high-speed, high accuracy, compact and low cost systems.

Development

- High speed system (2000~50000fps)
- Ultra high-speed system (20Mfps)
- Compact and low-cost 3D camera

Applications

- On-line manufacturing inspection
- Human body motion
- MEMS
- Collision of car
- Stress wave propagation

Future projects

- Full-field -→ whole-space
- Real-time -→ High- speed
- Micro system
- Auto sensing
- Auto control
- Auto repair
- Eye for robot
- Speeding up
- Security and recognition
- Prolonging life of structure
- Energy saving
- Ubiquitous
- Fusion of DIC and Fourier transform method
- Strain measurement by Fourier analysis of natural pattern
- Digital holographic interferometry
- Stress wave propagation analysis

Acknowledgement

Advisers

- Takuo Hayashi
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- Takeshi Kunio
- Masahisa Takashi

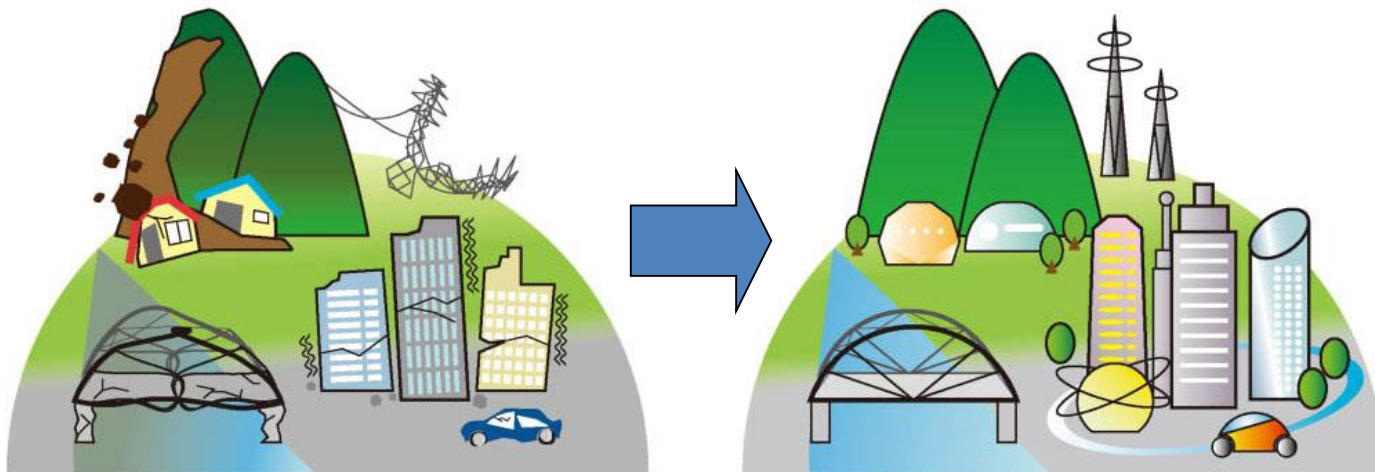


Many people

Colleagues

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- Yuko Yamamoto
- Shien Ri
- Akihiro Masaya
- Akifumi Takagi
- Yoshiyuki Kusunoki
- Masaki Ueki

Thank you for your attention



Without exp. mech.

With exp. mech.

Future town